

# MEMS Deformable Mirrors for Astronomical Adaptive Optics

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**ExEP Technology Colloquium Series**





# Outline

- BMC DM Technology
- DM Technology  
Development and  
Advancement
- Space astronomy operations
- Ground astronomy  
operation
- Conclusion

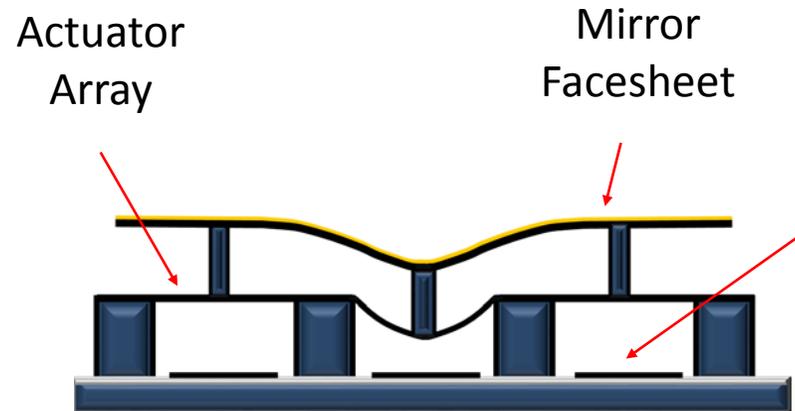


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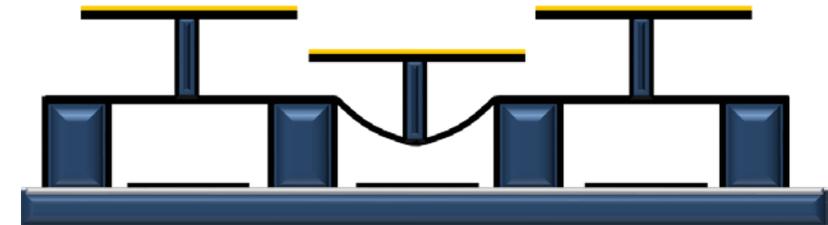


# MEMS DM Architecture

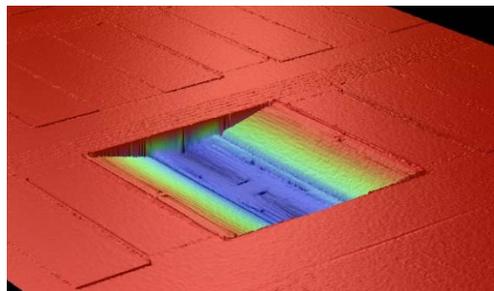


**Continuous mirror  
(smooth phase control)**

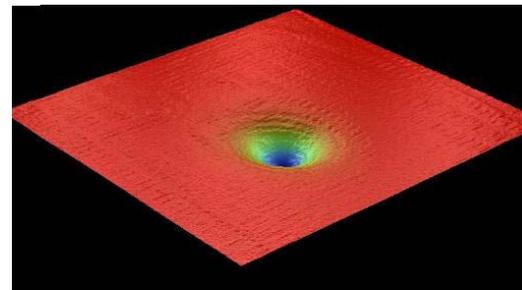
Actuator  
Electrode



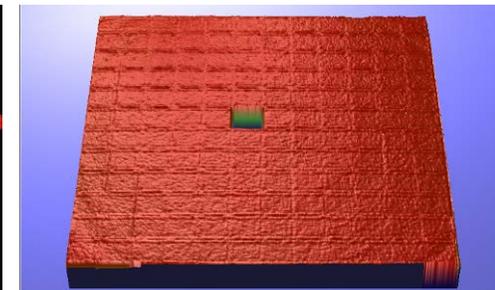
**Segmented mirror  
(uncoupled control)**



**Deflected Actuator**



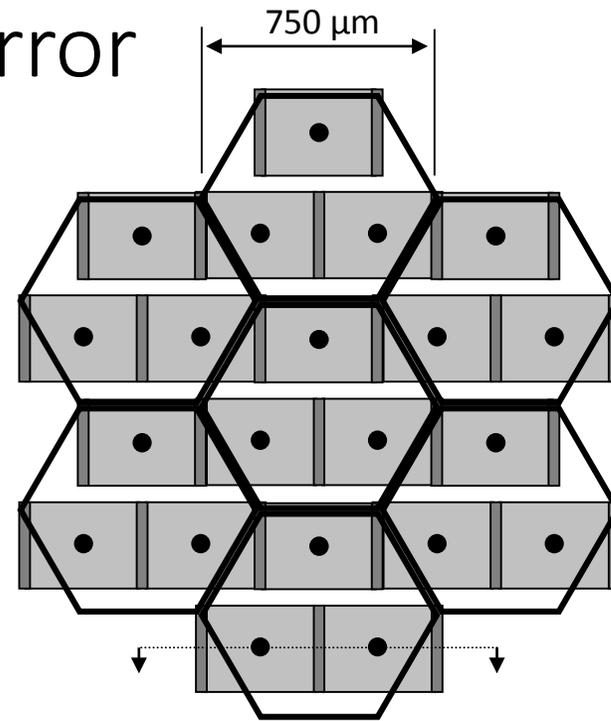
**Deformed Mirror  
Membrane**



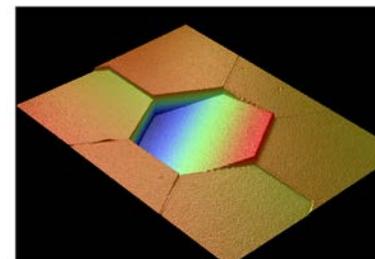
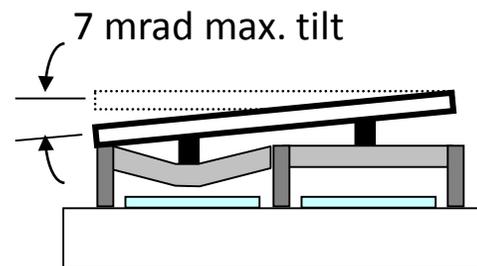
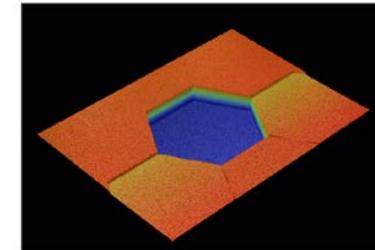
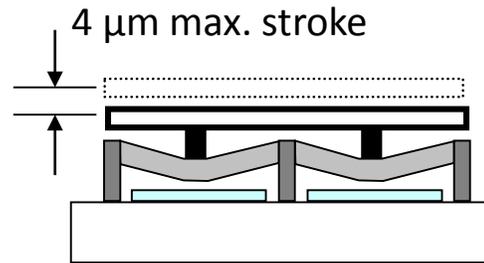
**Deformed  
Segmented Mirror**



# Hex Tip-Tilt-Piston Deformable Mirror



- Up to 3063 actuators
- Independent hexagonal segments
  - 3 actuators per segment
- 4  $\mu\text{m}$  max. stroke
- 7 mrad max. tilt angle



# BMC Mirror Family



## Small Cartesian Arrays

- Square arrays from 32 to 140 actuators
- Strokes: 1.5 $\mu$ m, 3.5 $\mu$ m or 5.5 $\mu$ m

## Medium Cartesian Arrays

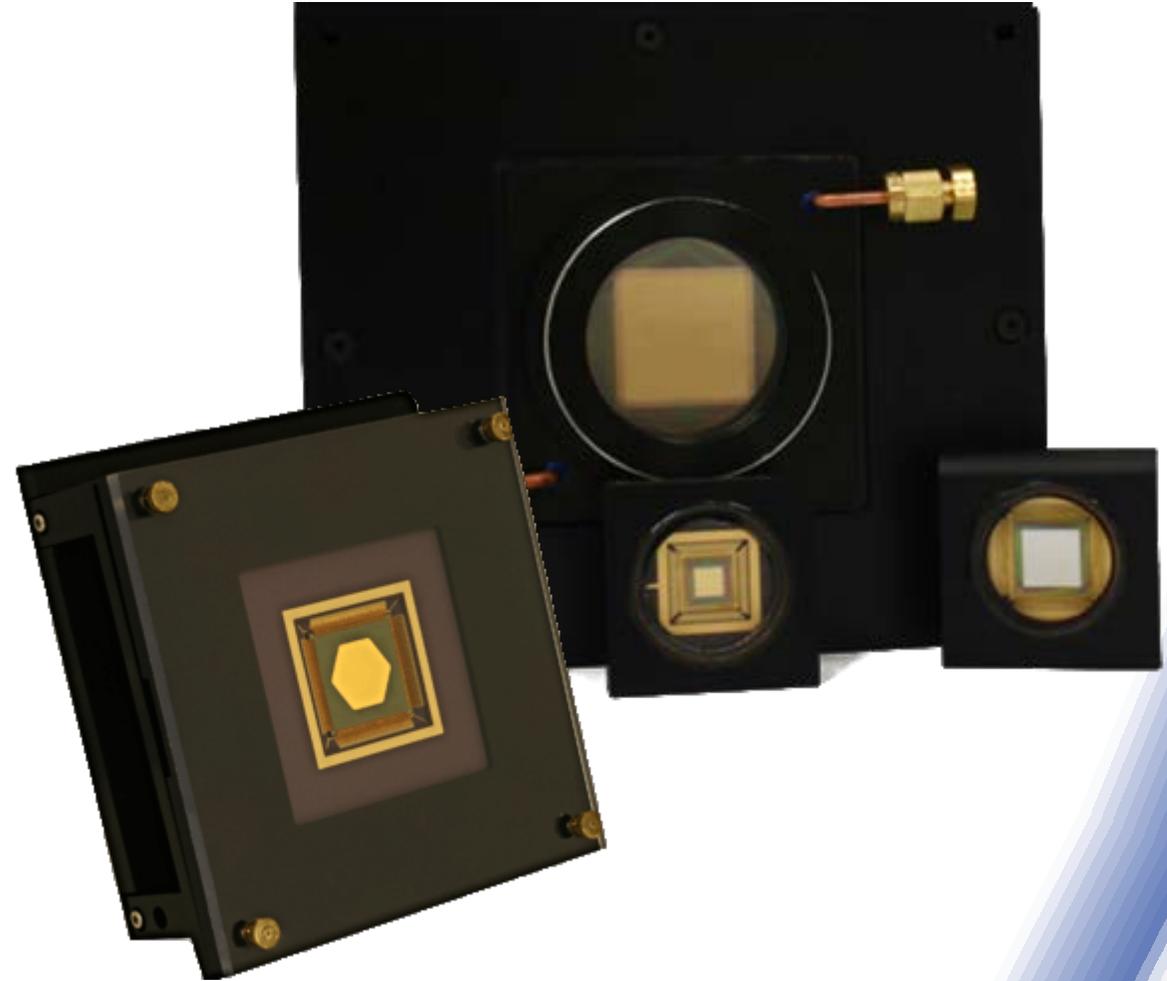
- Square and circular arrays from 492 to 1020
- 1.5 $\mu$ m & 3.5 $\mu$ m stroke

## Large Cartesian Arrays

- Square and circular arrays from 2040 to 4092
- 1.5 $\mu$ m and 3.5 $\mu$ m stroke

## Hex Tip-Tilt-Piston

- 37, 331- and 1021-Segment Devices



# BMC Mirror Family



## Small Cartesian Arrays

- Square arrays from 32 to 140 actuators
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## Medium Cartesian Arrays

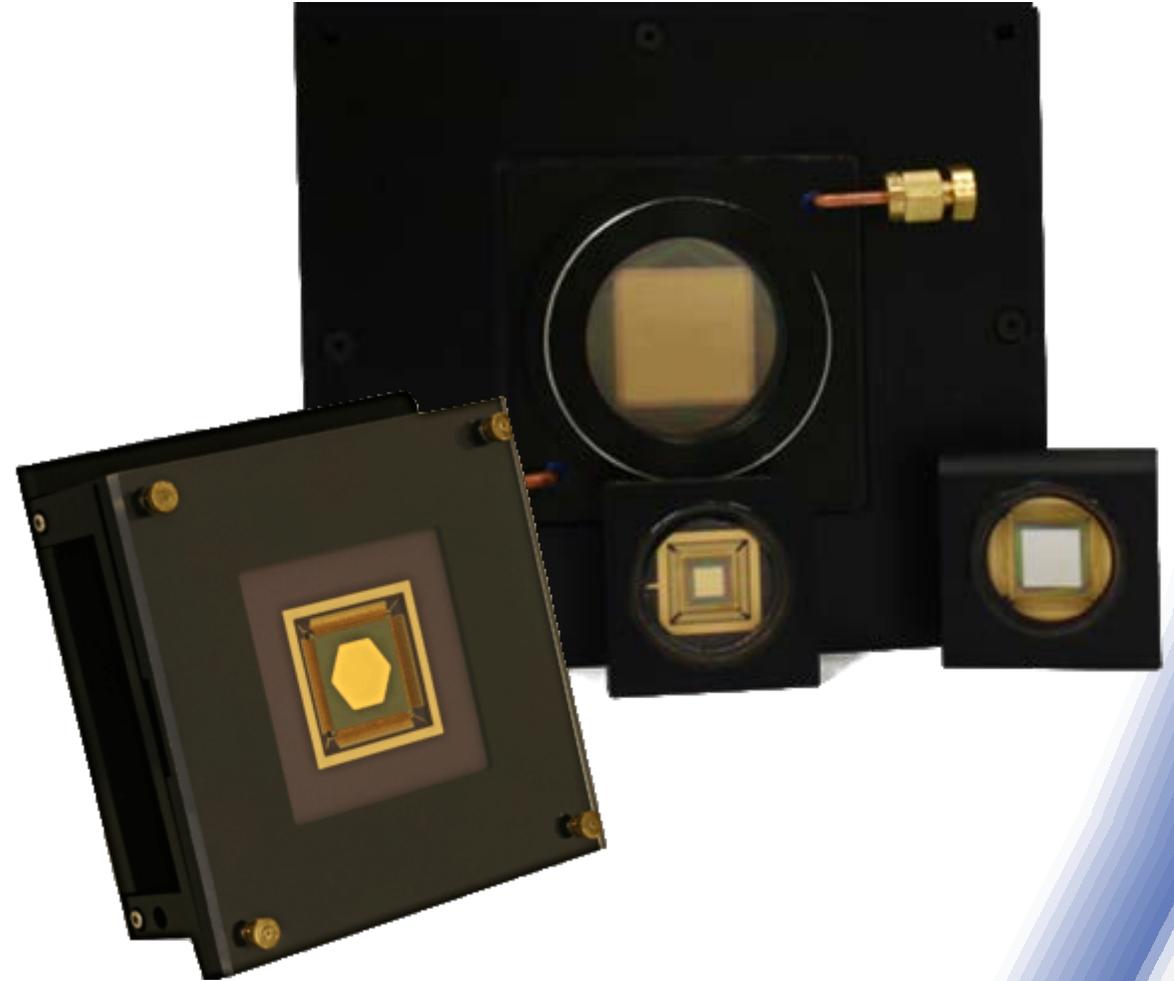
- Square and circular arrays from 492 to **1020**
- 1.5 $\mu$ m & 3.5 $\mu$ m stroke

## Large Cartesian Arrays

- Square and circular arrays from **2040** to 4092
- 1.5 $\mu$ m and 3.5 $\mu$ m stroke

## Hex Tip-Tilt-Piston

- 37, **331- and 1021-Segment Devices**



Developed through NASA funding

# MEMS DM Fabrication

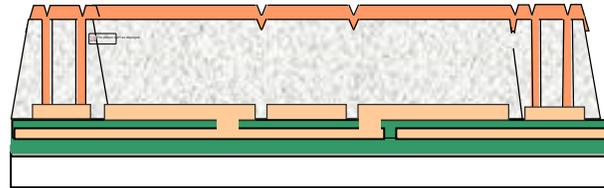
(deposit, pattern, etch, repeat)



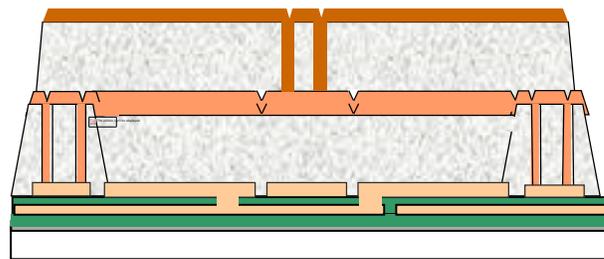
Electrodes & wire traces:  
polysilicon (conductor) & silicon nitride (insulator)

Ground  $8\mu\text{m}$

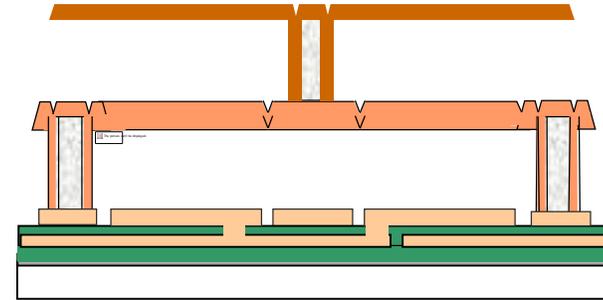
Space  $5\mu\text{m}$



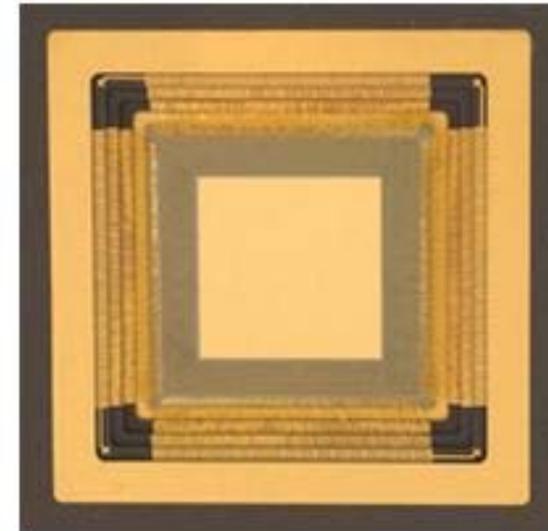
Actuator array:  
oxide (sacrificial spacer) and polysilicon (actuator structure)



Mirror membrane:  
oxide (spacer) and polysilicon (mirror)



MEMS DM:  
Etch away sacrificial oxides in HF, and deposit reflective coating



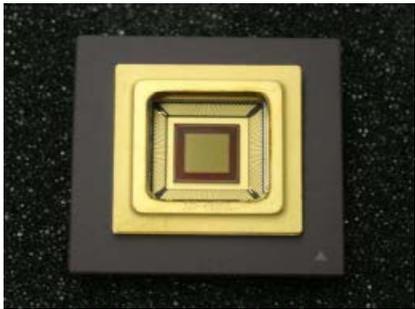
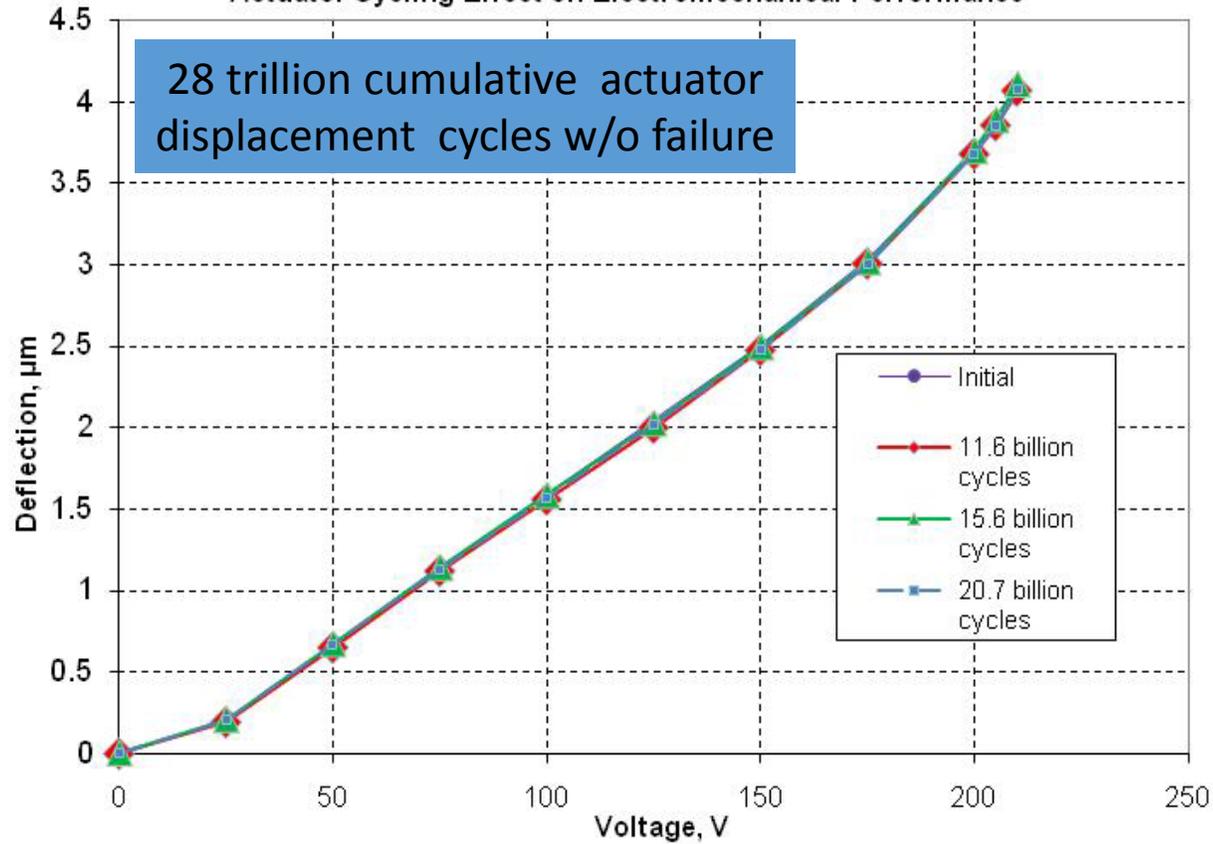
Attach die to a ceramic package and wirebond

# MEMS DMs Characteristics

## Reliable



Actuator Cycling Effect on Electromechanical Performance





# MEMS DMs Characteristics

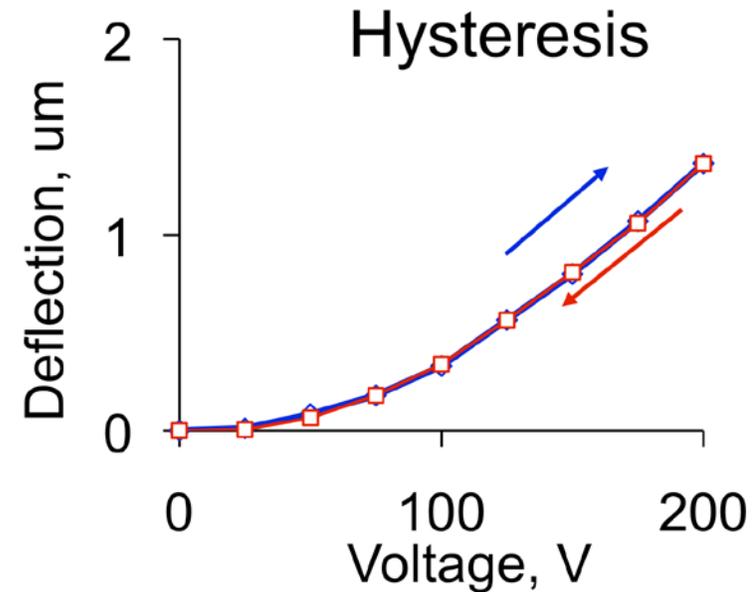
## Repeatable and Stable

- Repeatability:
  - 97% of the actuators returned to a commanded shape to under 1.0 nm phase
  - 73% of the actuators returned to a commanded shape to under 0.4 nm phase
- Stability:

	1.33 min	8 min	38 min
MEMS MIRROR	0.088nm	0.106nm	0.150nm
Reference Flat	0.042nm	0.116nm	0.122nm



Morzinski et al, *Characterizing the potential of MEMS deformable mirrors for astronomical adaptive optics* 2016SPIE.9909E..01M





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# Technology Research

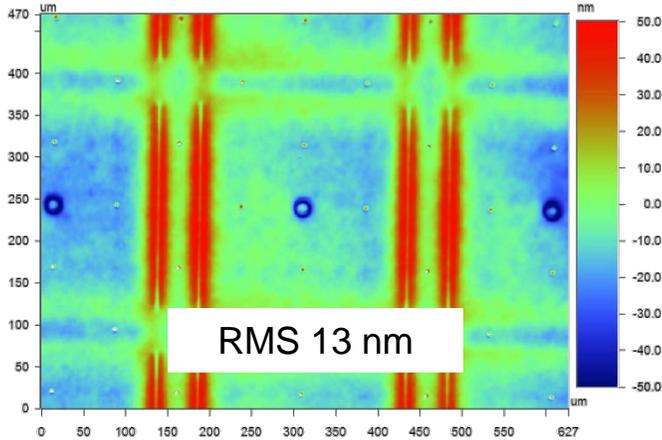
Over the past years BMC has performed research and development for the improvement of MEMS DM for space applications

- Topography
- Yield
- Reliability
- Reduced operating voltage
- Hex TTP development
- Technology development

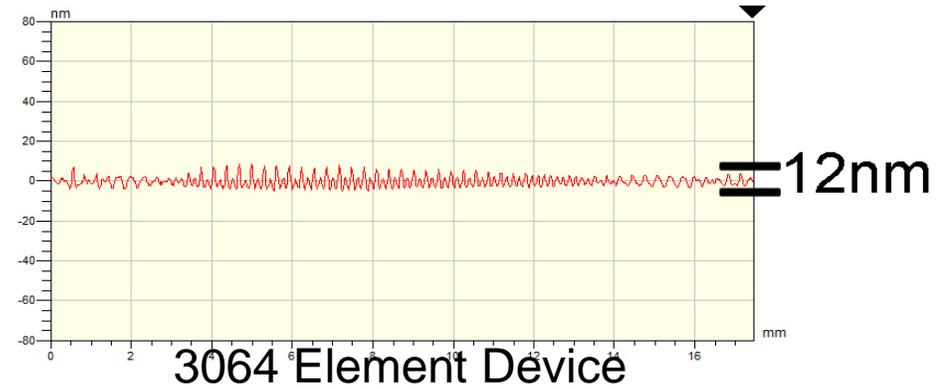
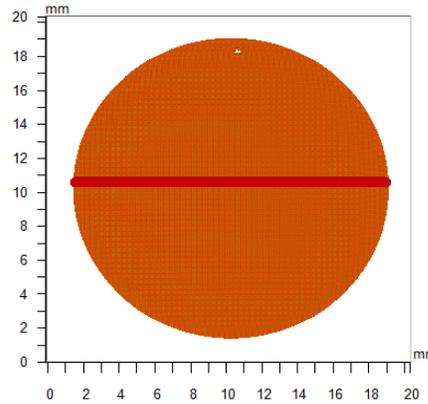
# Topography Improvements



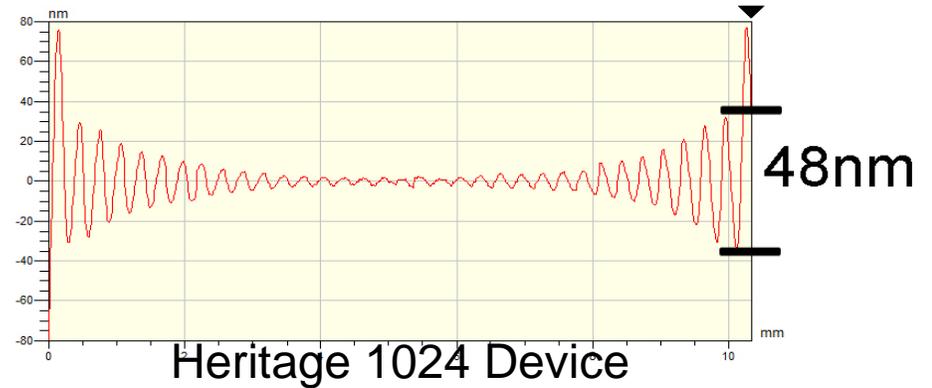
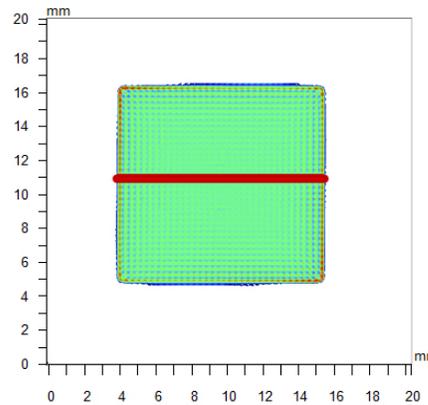
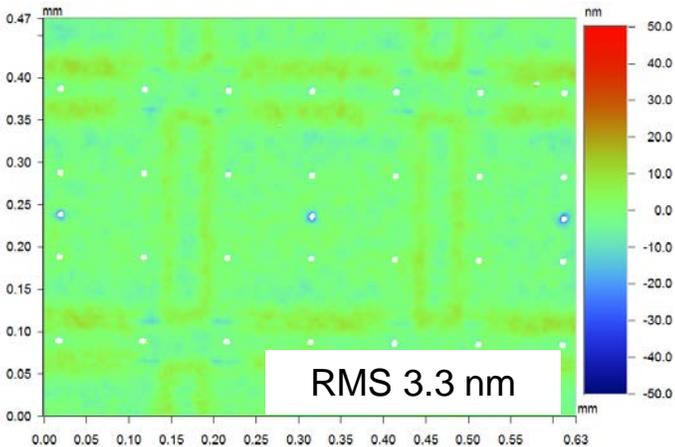
## Heritage Process



## Scalloping across mirror compared to heritage devices

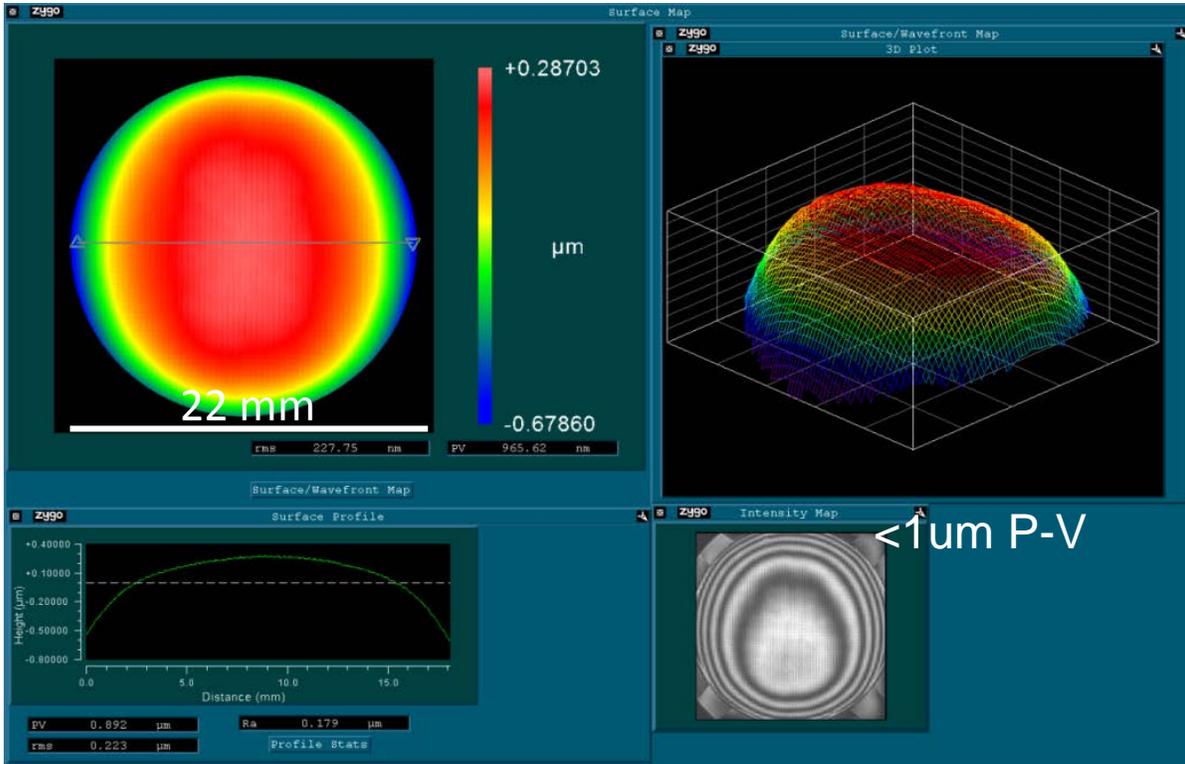


## Modified Process

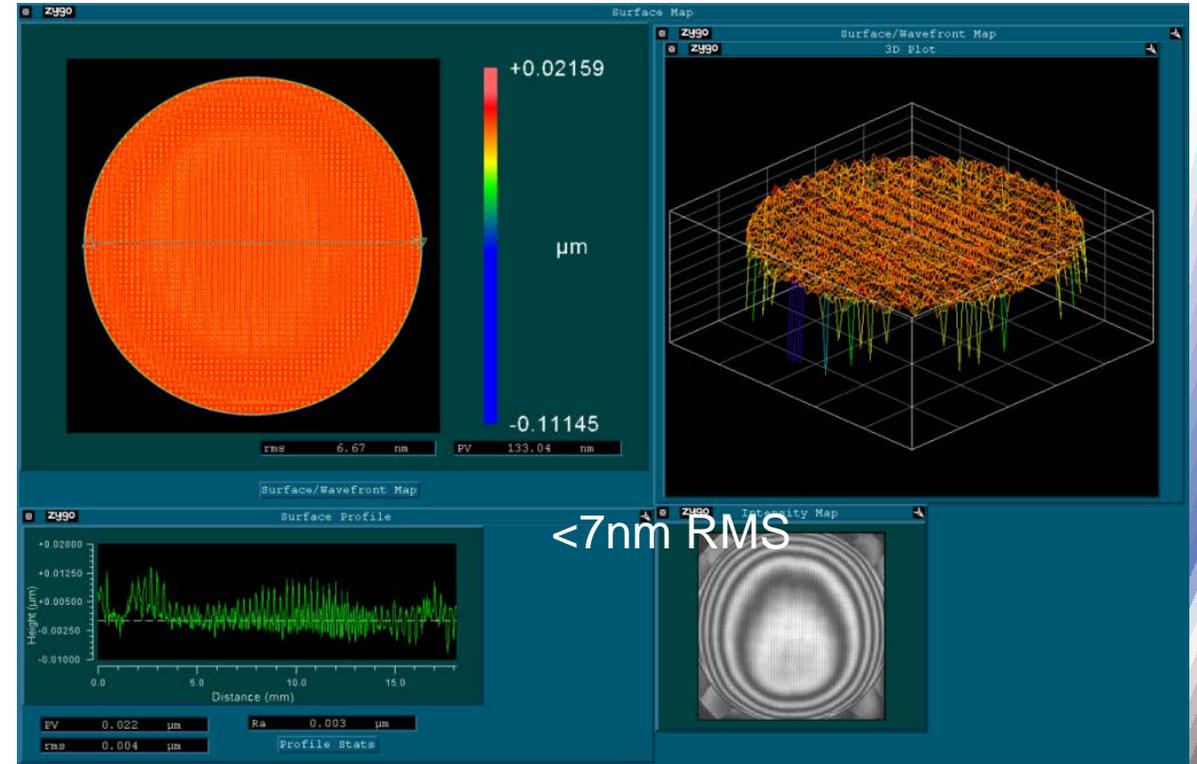


*Note 3064 aperture is 17mm while heritage is 10mm*

# Topography Improvements



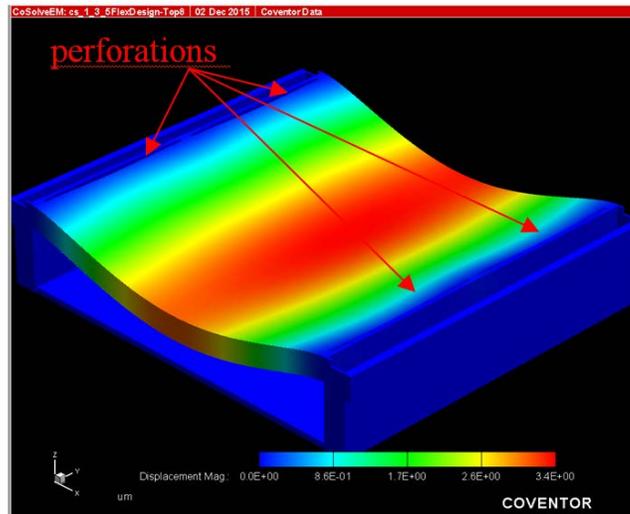
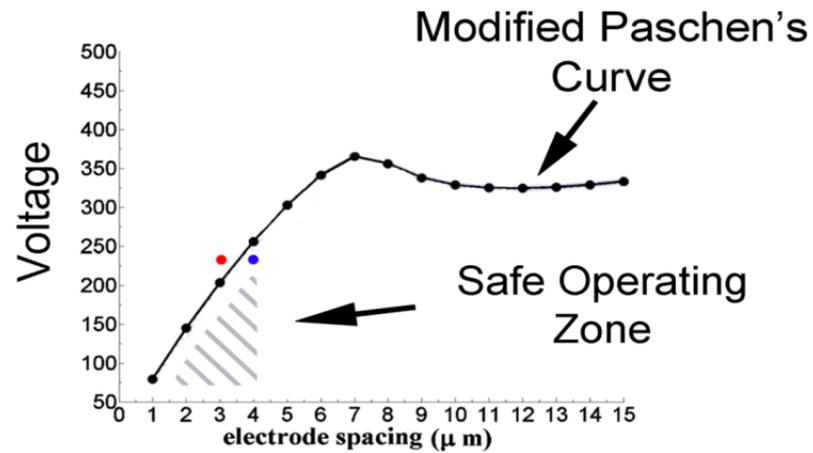
Unpowered Surface



With low order filtered  
(control bandwidth)



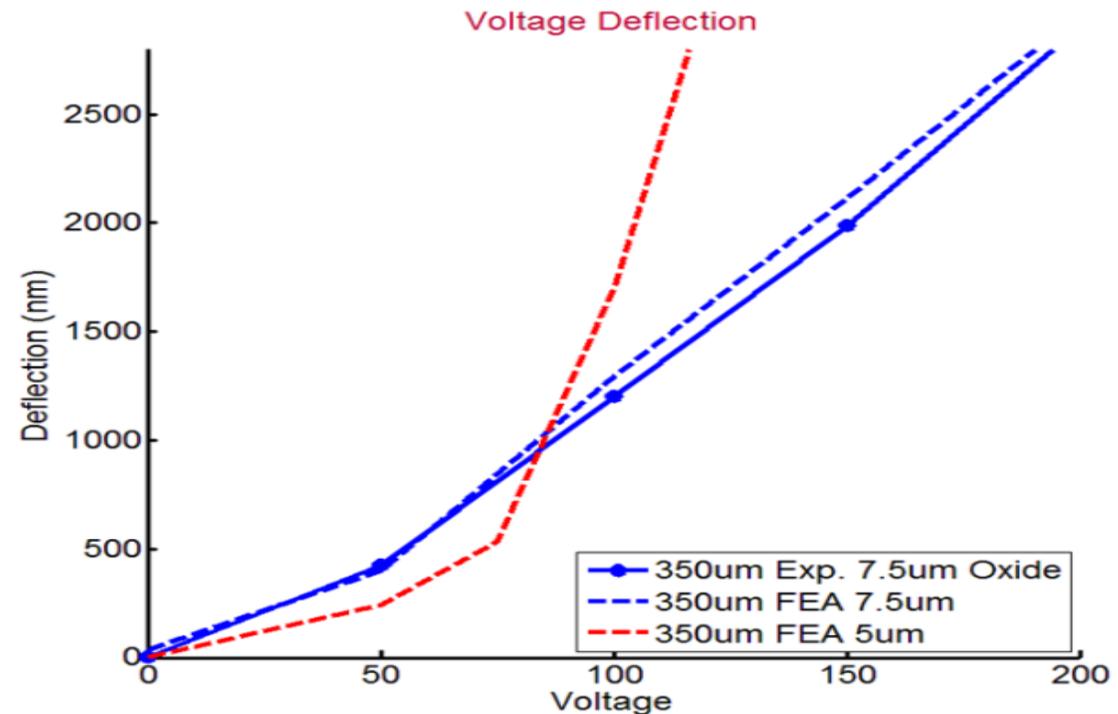
# Reduction in Operating Voltage (Ongoing)



Modified design allows full actuation at lower voltage

## Reduced Operating Voltage

- Lower power usage
- Easier electronics
- Safer operation

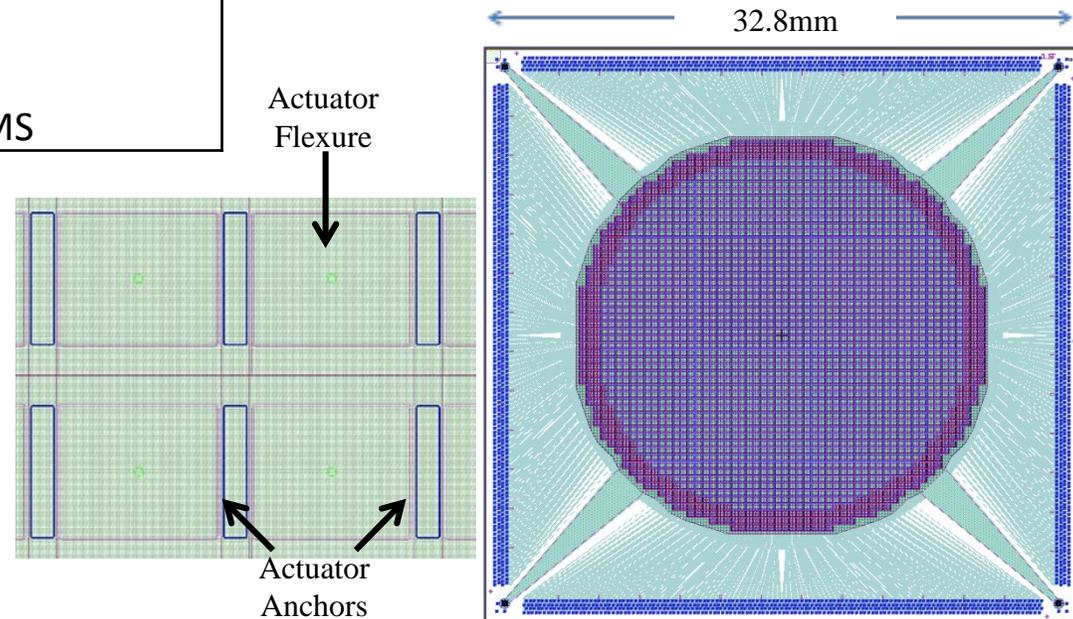
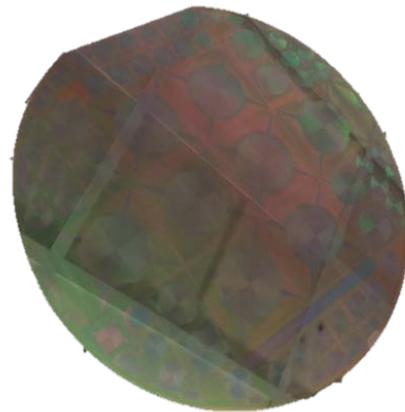
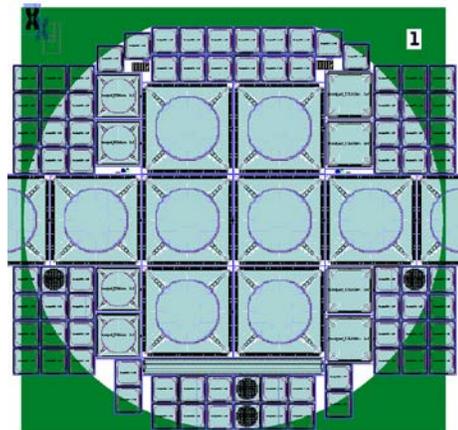
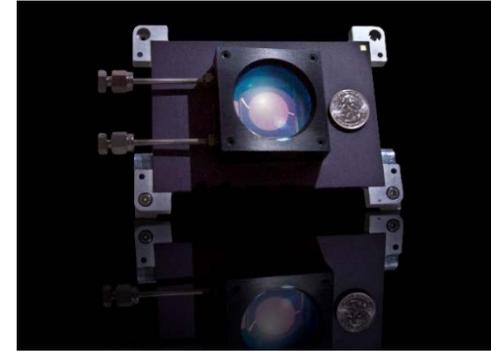




# Improved Yield, Performance and Reliability of High-Actuator-Count Deformable Mirrors

Contract Number: NNX16CP14C (Start 4/2016)

Mirror architecture	2040 actuators
Active Aperture Diameter	19.6mm
# Actuators across active diameter	50
Actuator Pitch	400 $\mu$ m
Actuator Stroke	1.5 $\mu$ m
Operating Voltage	0-100V
Mirror Surface Figure	<5nm RMS



Layout of a 2040-actuator device design (Right), showing all nine mask layers required to form the MEMS deformable mirror.

# TDEM Program



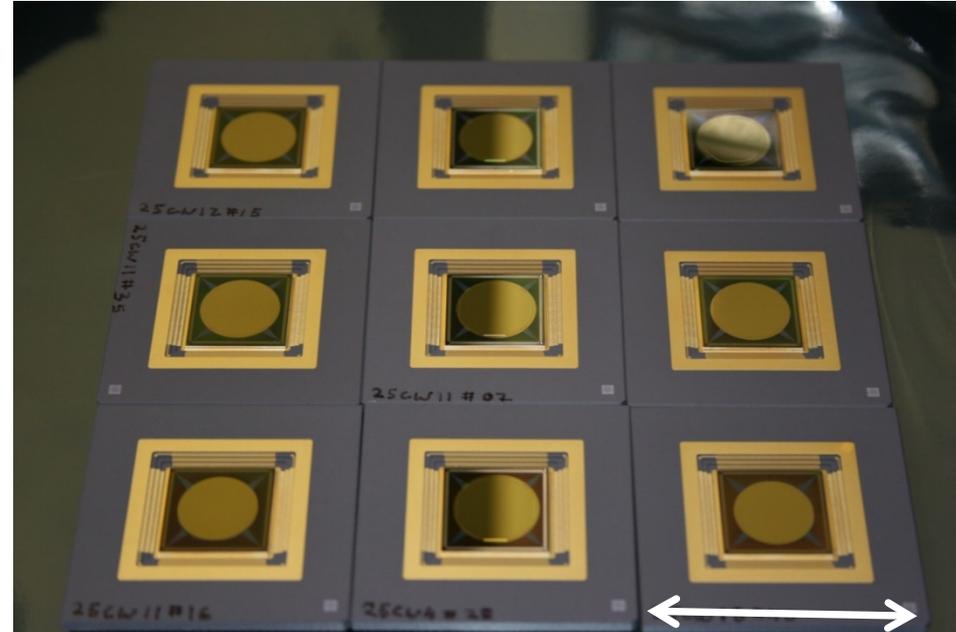
**Ongoing Contract#: NNH12CQ27C**

**TDEM/ROSES**

*MEMS Deformable Mirror Technology  
Development for Space-Based Exoplanet  
Detection*

Objective: Demonstrate survivability of the BMC MEMS Deformable Mirror after exposure to dynamic mechanical environments close to those expected in space based coronagraph launch.

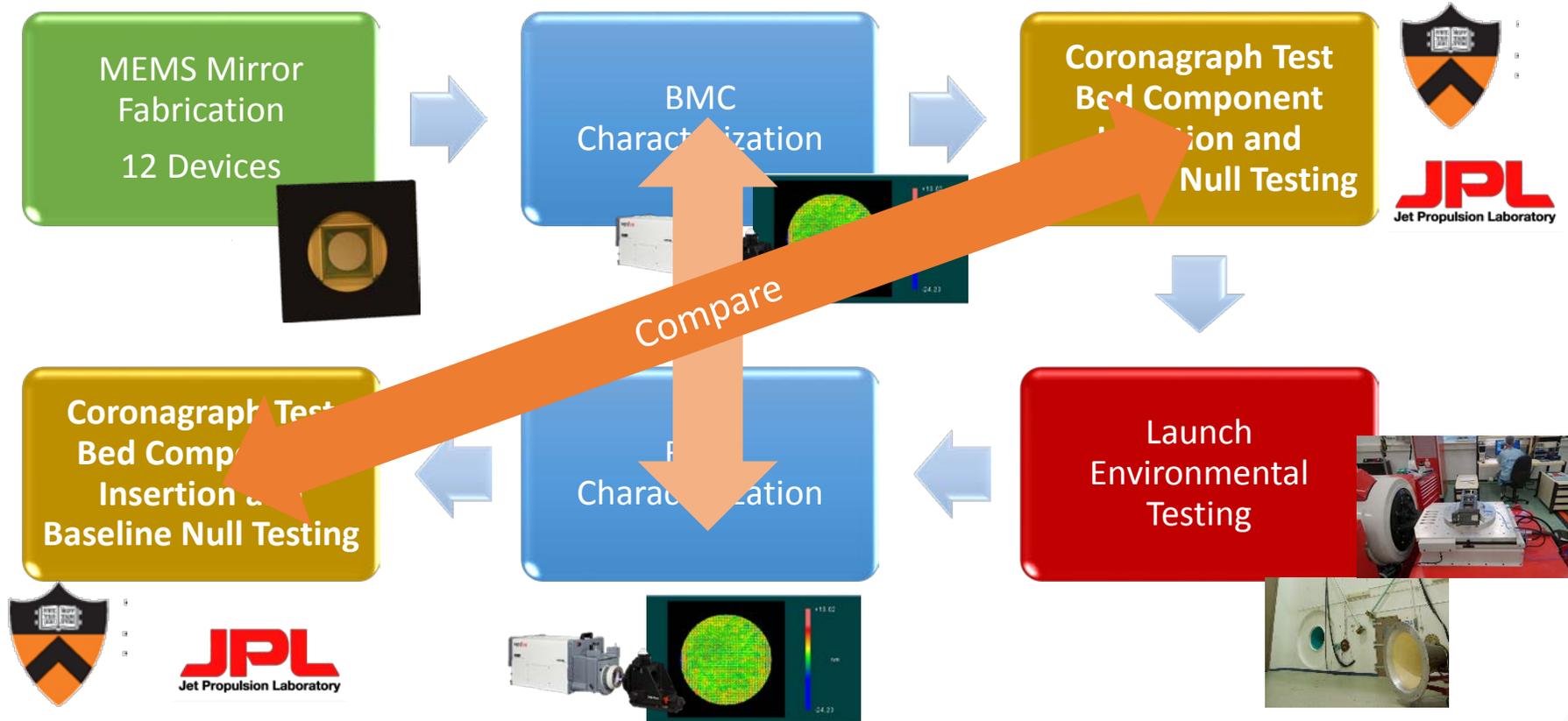
9 Mirrors ready for testing



**5cm**



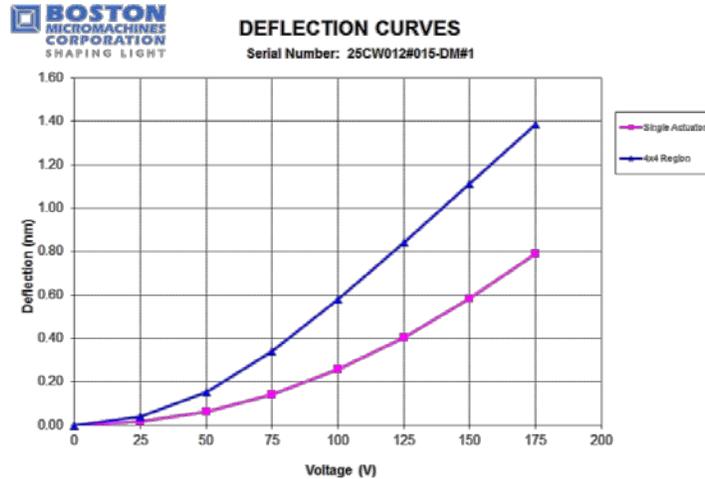
# Project Flow



# 12 DMs Fabricated and Characterized

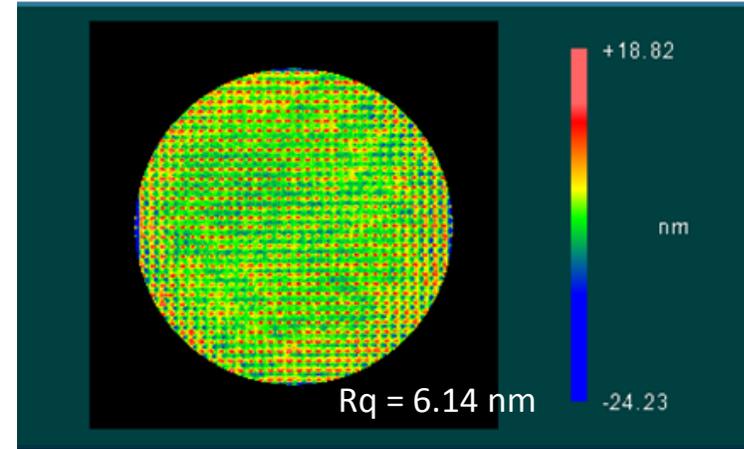


### Voltage v. Deflection

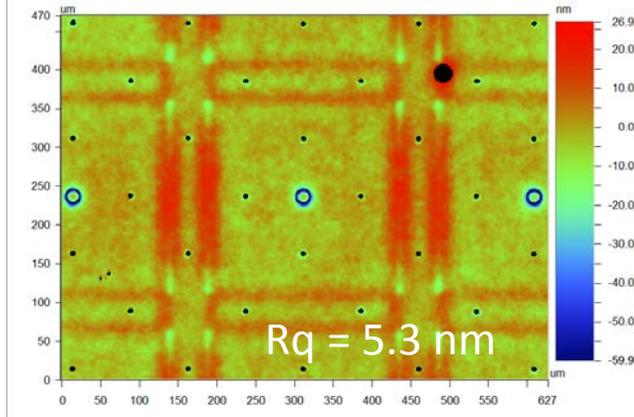


### Active Flattening of DM Surface

Continuous DM Surface Data  
Powered Flat Image Circular Aperture  
(Tilt Removed)

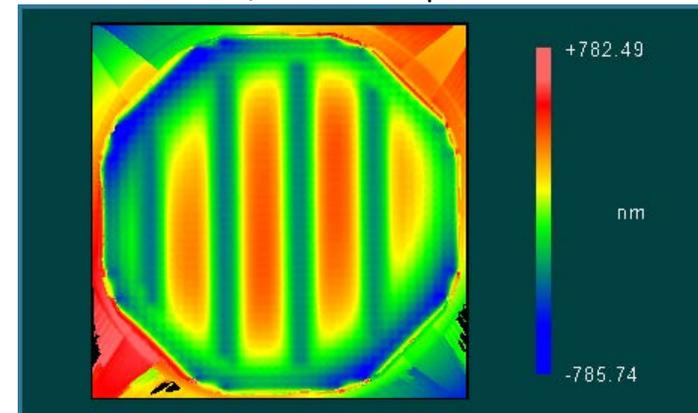


### Single Actuator Surface Figure



### Sinusoid Shape

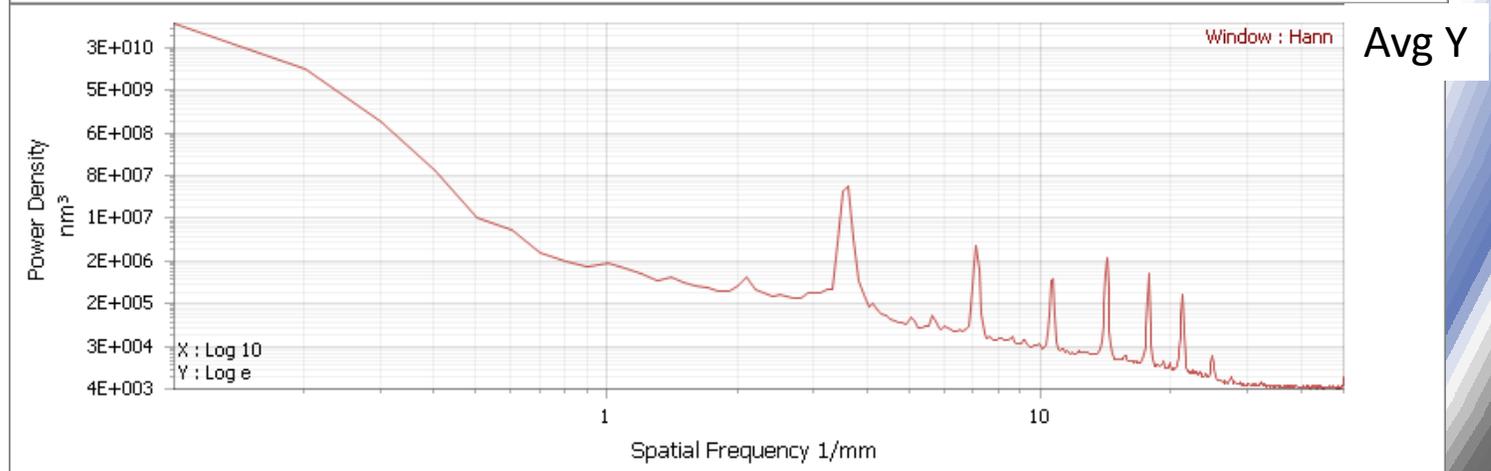
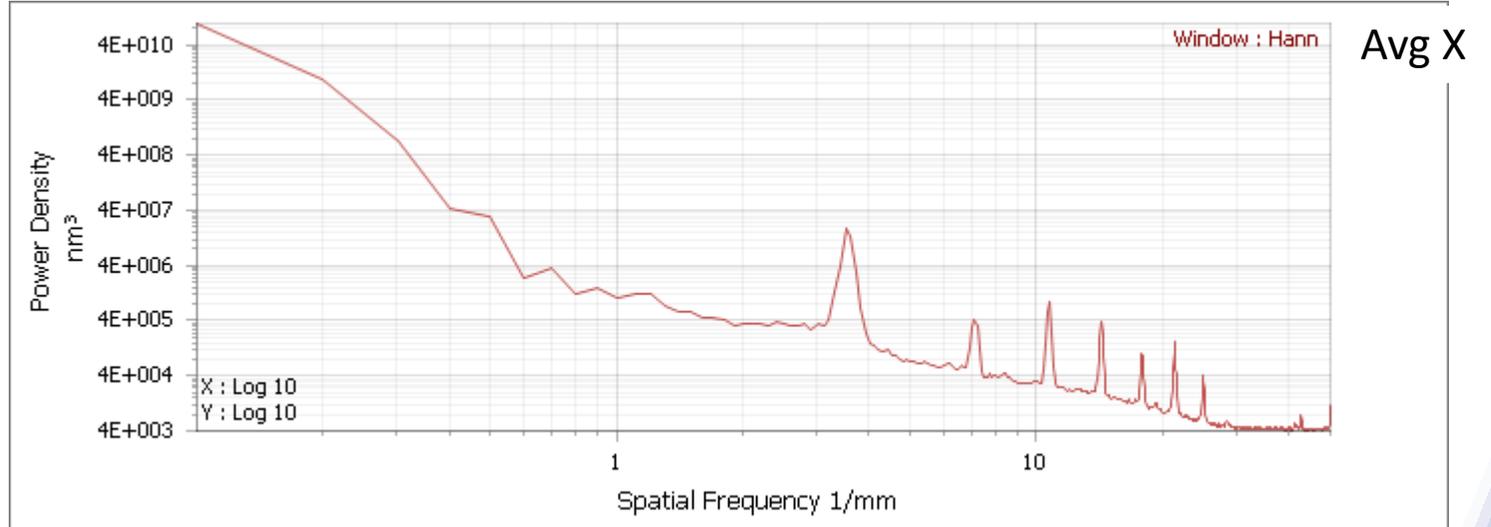
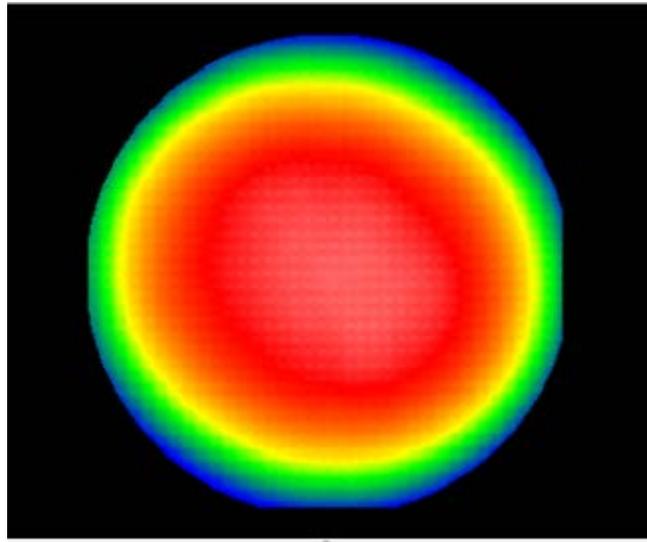
4 Period, 400nm Amplitude



Delivered to JPL (2) and Princeton (2)



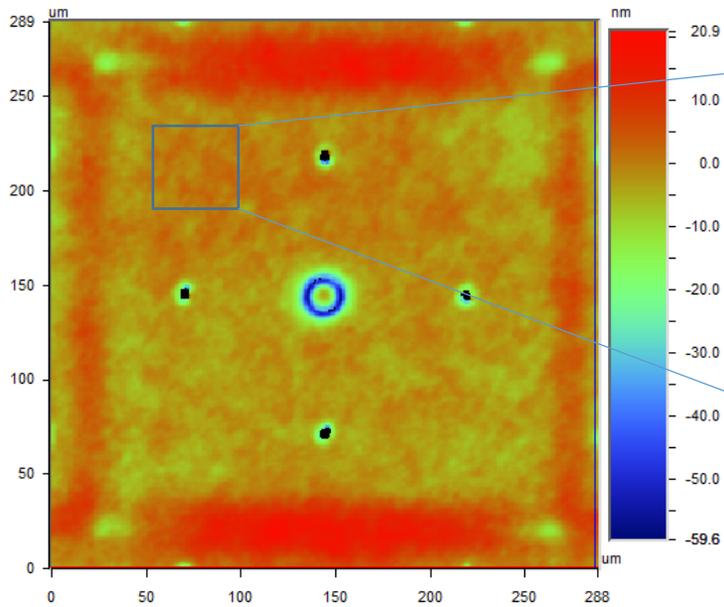
# Power Spectral Density





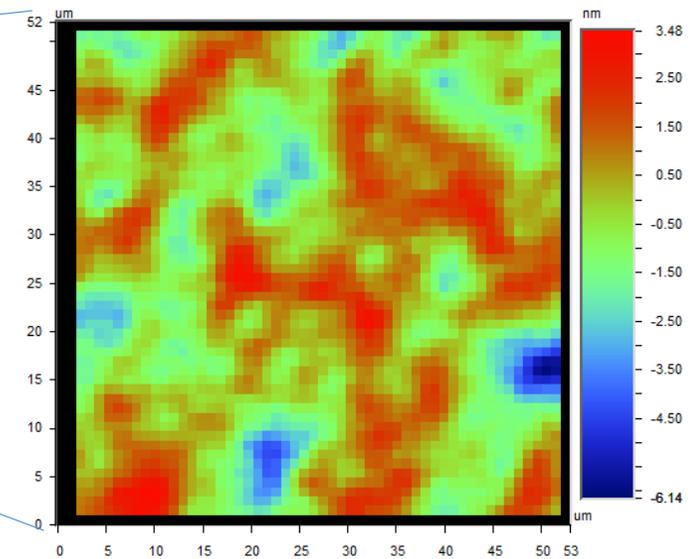
# Surface Finish and Figure of MEMS DMs

<b>Surface Statistics:</b>
Ra: 3.89 nm
Rq: 5.86 nm
Rz:
Rt: 80.54 nm
<b>Set-up Parameters:</b>
Size: 295 X 296
Sampling: 981.05 nm
<b>Processed Options:</b>
Terms Removed:
Tilt
Filtering:
None



Single Actuator (300 $\mu$ m x 300 $\mu$ m)  
RMS – 5.9 nm

<b>Surface Statistics:</b>
Ra: 1.09 nm
Rq: 1.36 nm
Rz:
Rt: 9.62 nm
<b>Set-up Parameters:</b>
Size: 55 X 54
Sampling: 981.05 nm
<b>Processed Options:</b>
Terms Removed:
None
Filtering:
None



Micro-roughness (50 $\mu$ m x 50 $\mu$ m)  
RMS – 1.4 nm

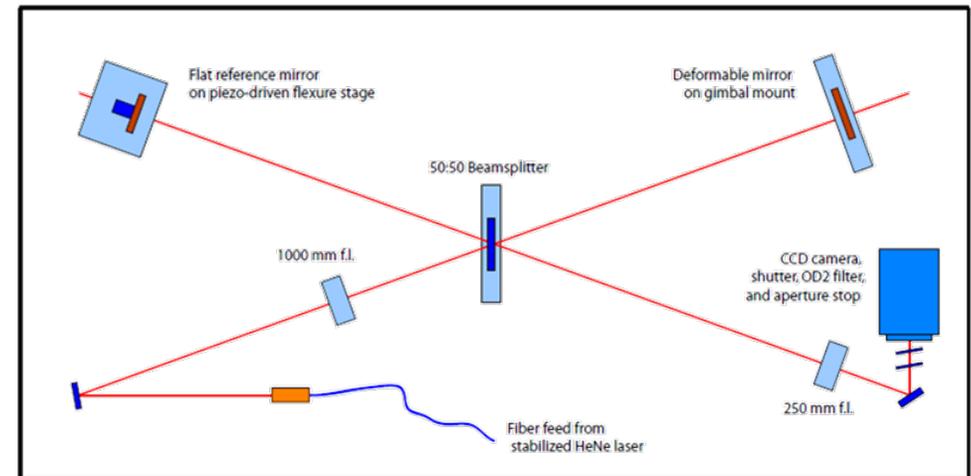


# Vacuum Surface Gauge (VSG) Measurements

Two 952 actuator MEMS DMs (tested separately)

- Surface figure of DM at zero bias
- Surface figure of DM for flat surface
- Actuator gains for all 952 actuators for small up/down pokes about the flat surface condition
- Drift in surface for “flat” condition for 48 hour period
- Repeatability from “flat” and BMC/JPL solution for 10 repeats

Work performed by: Frank Greer, Cory Hill, Brian Gordon, John Trauger

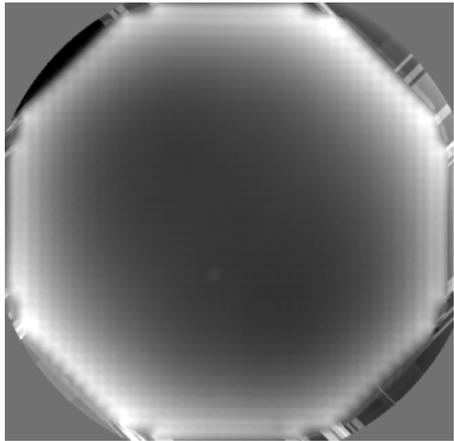


- VSG is a Michelson interferometer mounted in a vibration isolated vacuum chamber
- Light source is 632.8 nm frequency HeNe laser
- Reference mirror is mounted on a piezo-driven flexure translation stage
- Deformable mirror under test is on a gimbal mount with a temperature controlled stage

# Flattening Protocol

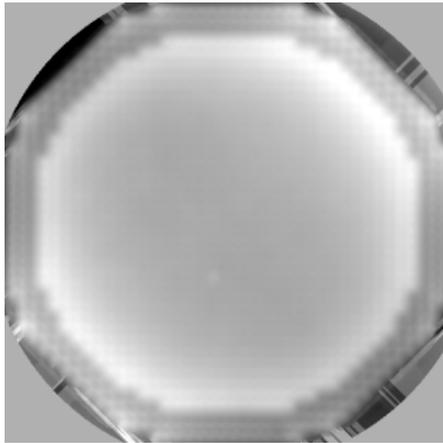


Unpowered mirror



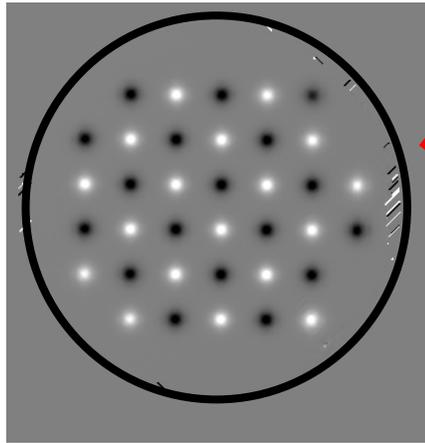
PV Focus 1428 nm, PV 45° astig 360 nm, PV 90° astig 3 nm, RMS in higher 110 nm

Mirror with 100V bias



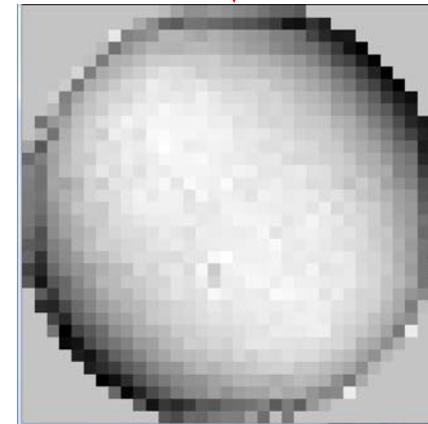
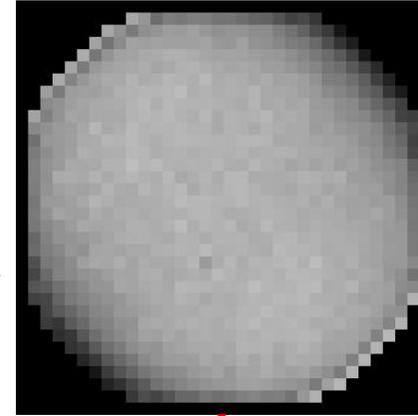
PV Focus 667.3 nm, PV 45° astig 257 nm, PV 90° astig 17.3 nm, RMS in higher 48 nm

5 x 5 array of +/- 10 V pokes  
(difference of two images, circle drawn for clarity)



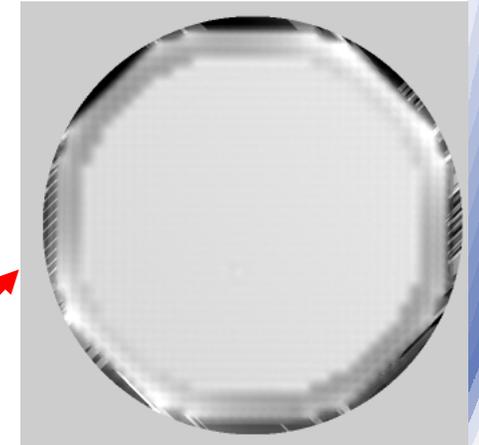
Pokes used to measure gains and calculate voltage map for flat surface figure

Actuator gain map measured about "flat" condition  
(5-10nm/V range)



Voltage map for flat surface figure centered about 100V  
(55 – 112V range)

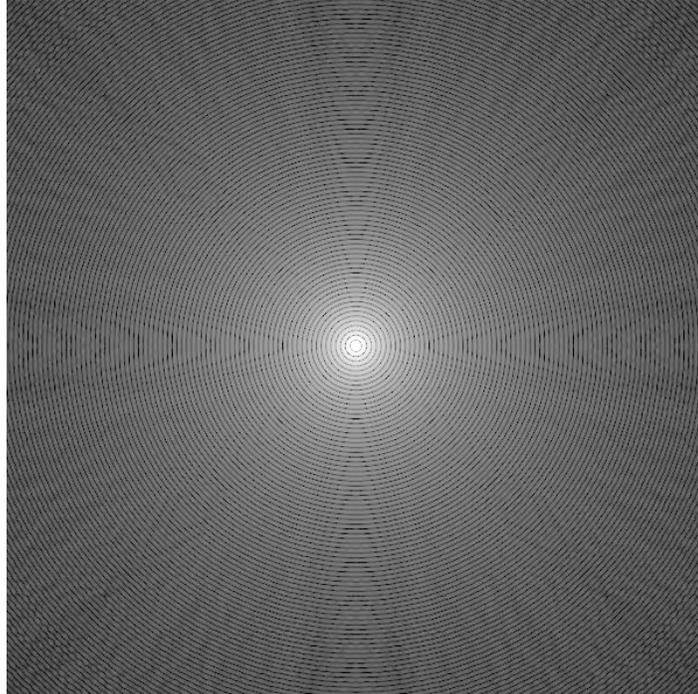
Flattened DM



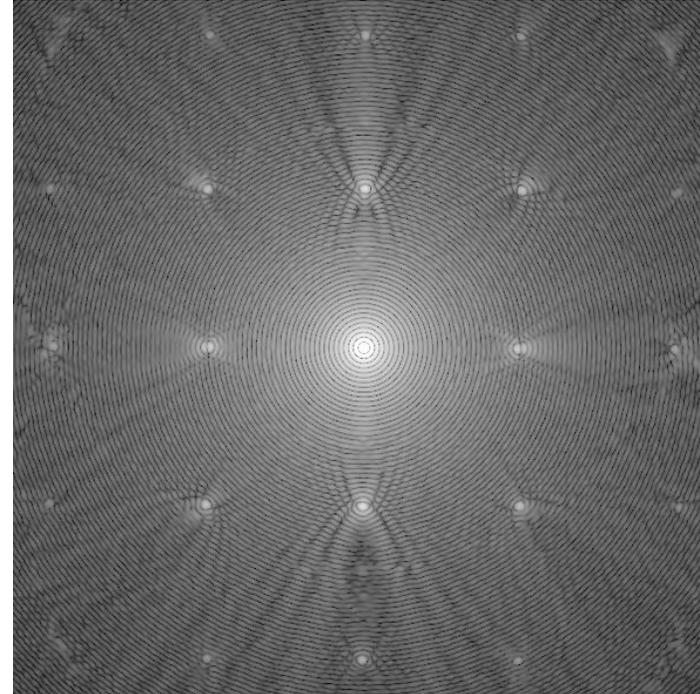
6.6nm PV focus, 2.9nm PV 45 deg astig, 0.3nm PV 90 deg astig, 7.6nm RMS higher order terms



# Point Spread Function for the best flat setting



PSF with mathematically flat surface



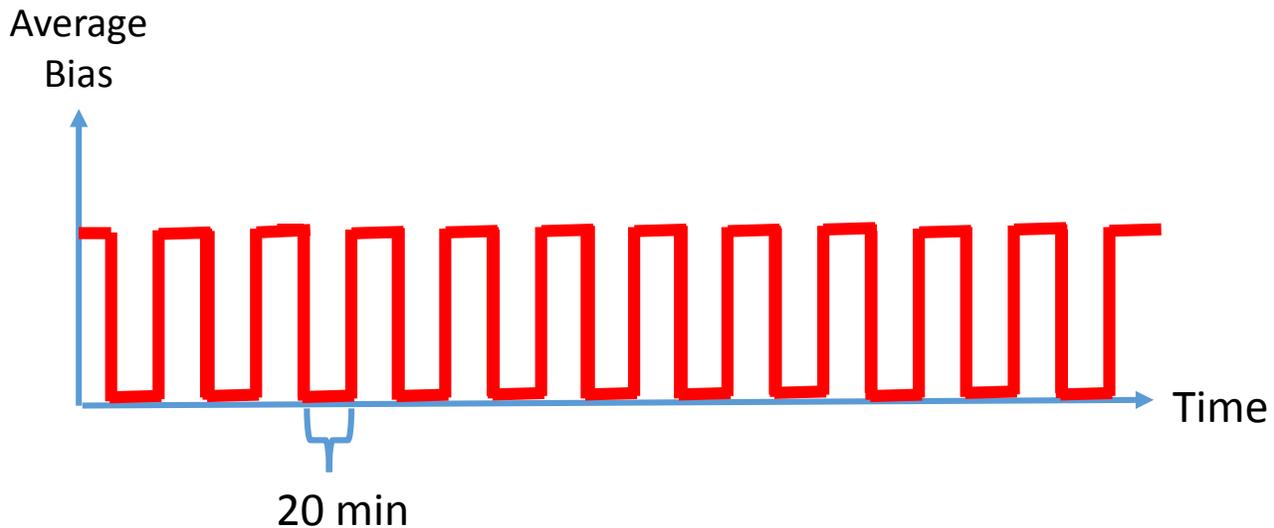
PSF with best flat BMC  
(quilting = 7.5 nm RMS)

Strehl at 633 nm wavelength for the quilted BMC surface = 0.96

# Accuracy and Stability Protocols (using the flattened DM)

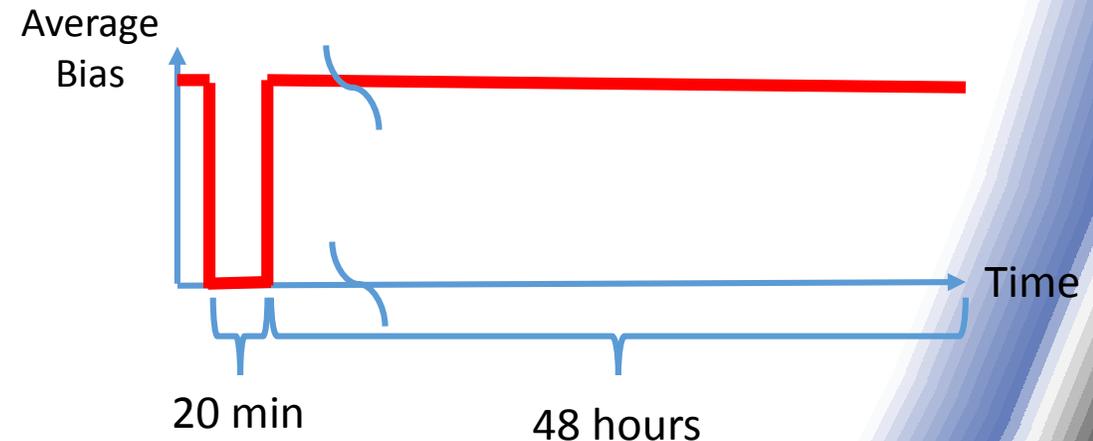


- Tested repeatability of a flat surface figure solution ten times, passing through an unpowered state each time prior to applying the “flat surface figure solution”.



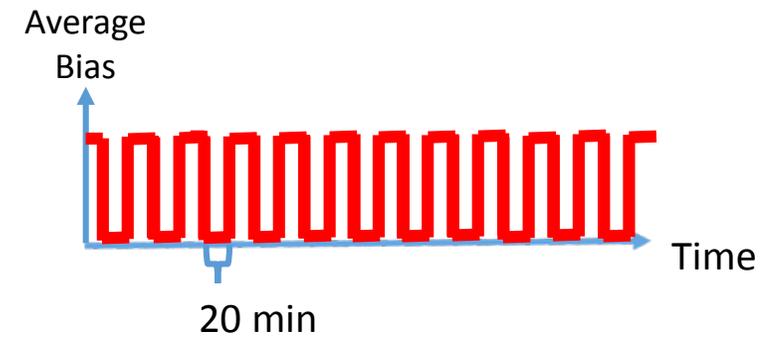
Two phase retrievals completed at the biased and unbiased condition for every repetition

- Tested settling time for the BMC mirror when applying the “flat surface figure solution” passing through an unpowered state for ~20 minutes prior to the beginning of the experiment. The mirror was left powered for with this solution and was characterized frequently over a 48 hour period.

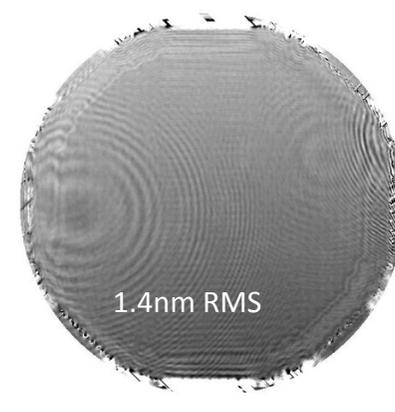
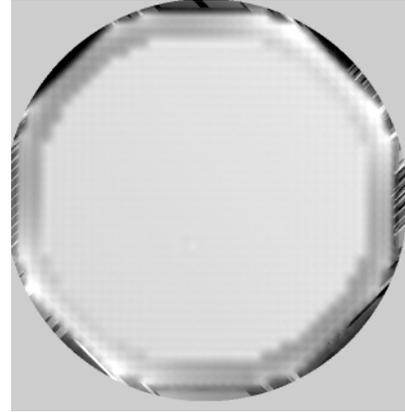
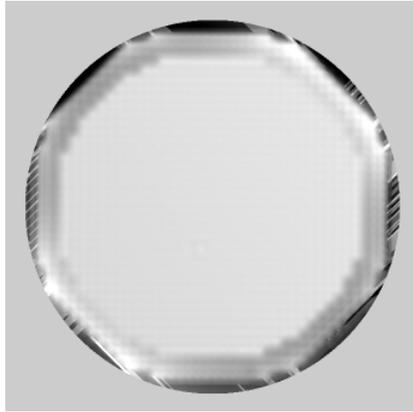


Phase retrievals completed after the following waiting periods:  
20 min, 1 hour, 2 hours, 4 hours, 8 hours, 16 hours, 24 hours, 32 hours, 40 hours, 48 hours

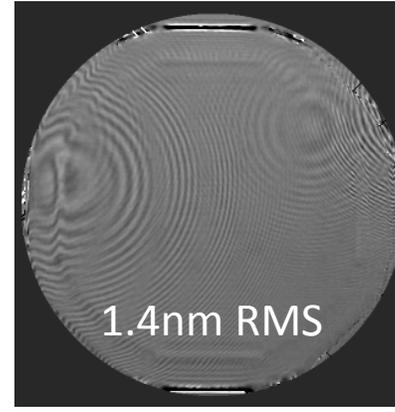
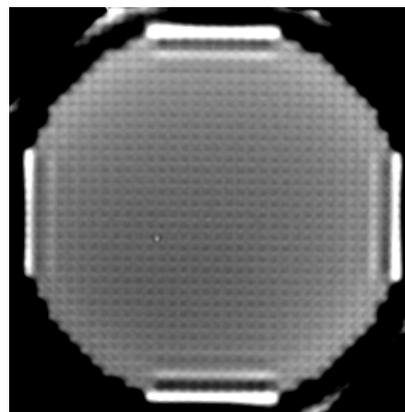
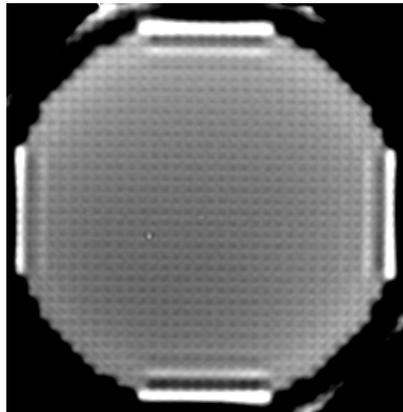
# Repeatability Test Results



DM1



DM2



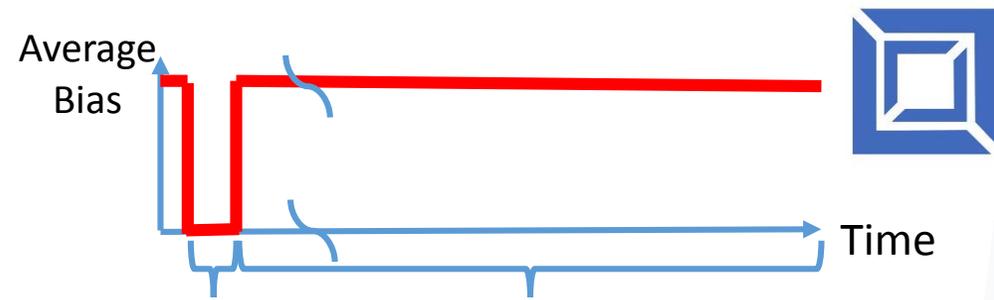
Initial "Flat" solution

"Flat" solution 10 iterations of zero volts to "flat"

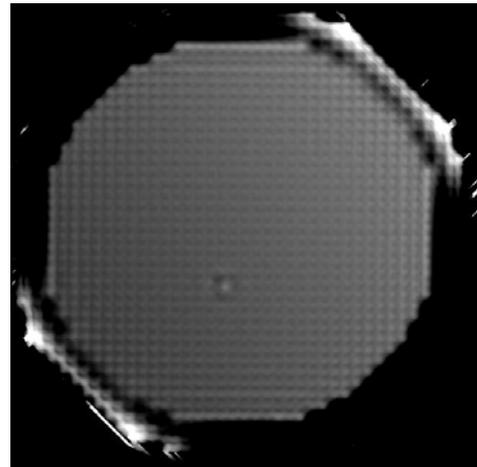
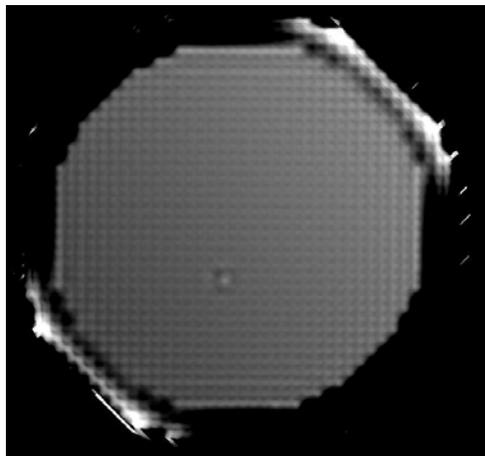
Difference Phase Map

No obvious differences between maps.

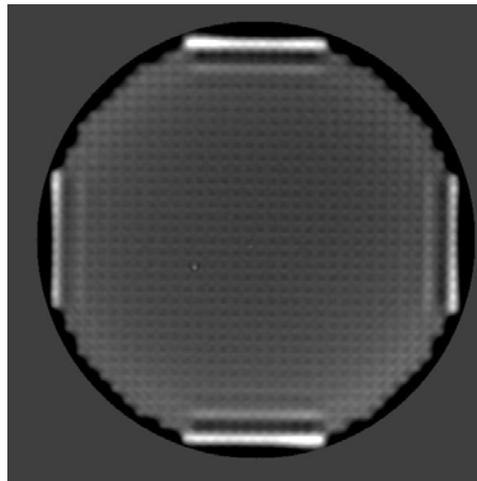
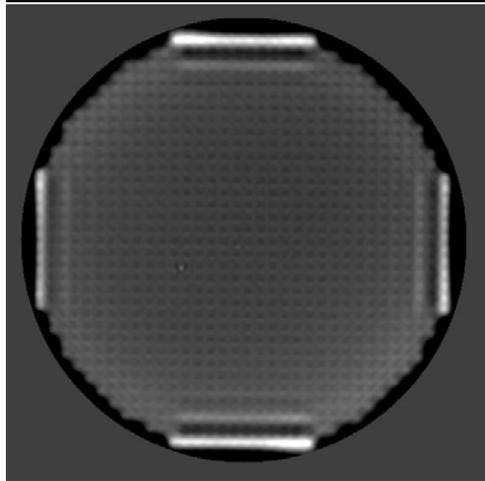
# Comparison of flats from settling test



DM1



DM2



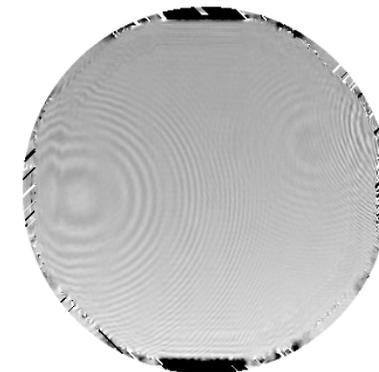
**First map**

**Last map**

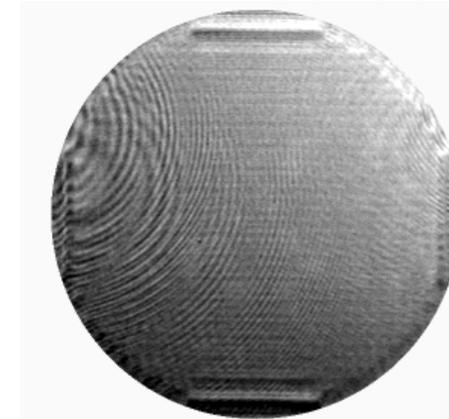
No significant changes observed in the settling time test ( )

20 min

48 hours



2.1nm RMS difference

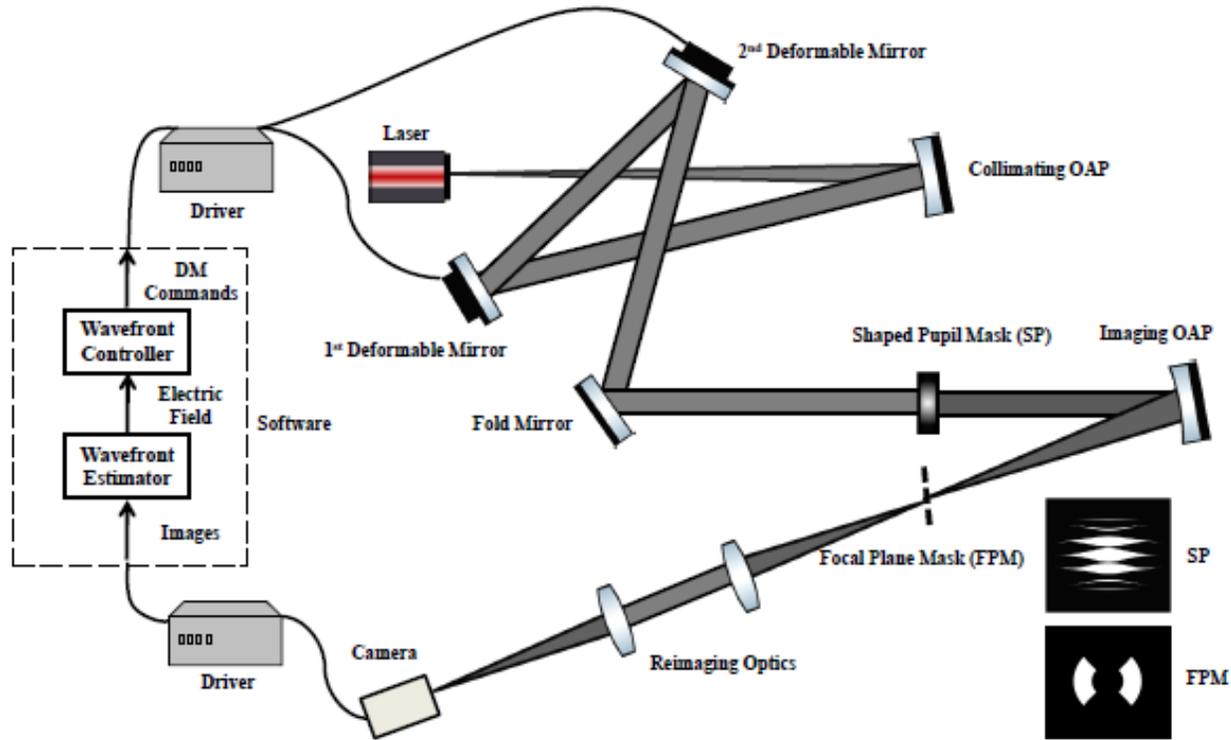


0.9nm RMS difference

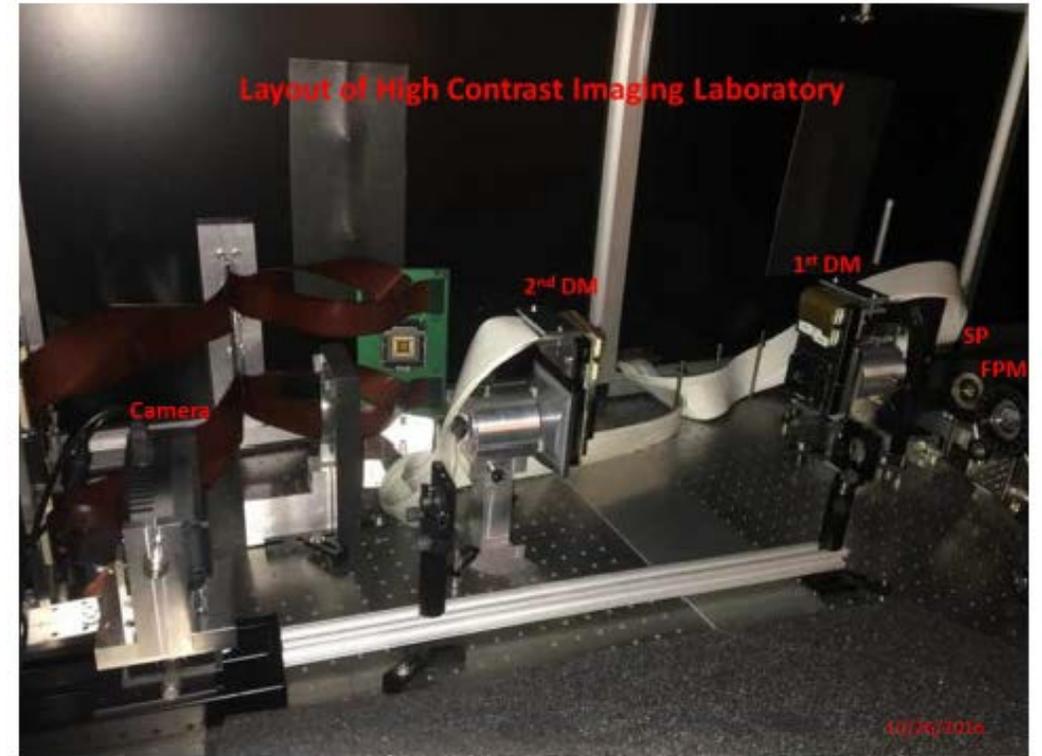


# High Contrast Imaging Laboratory(HCIL)

## Kasdin Lab, Princeton University



Concept diagram of HCIL layout.

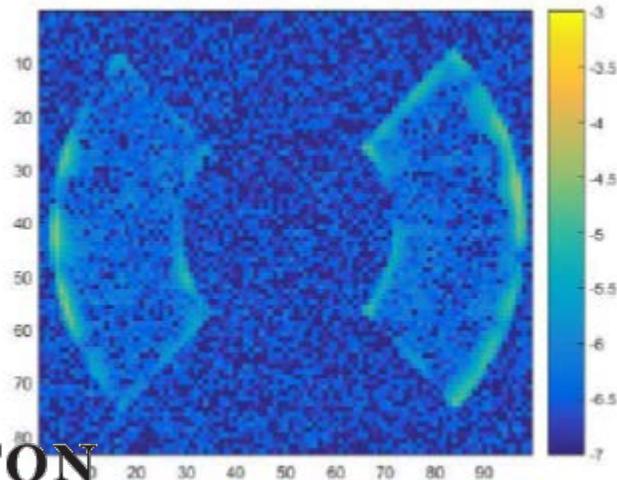


HCIL testbed image after implementing new DMs.

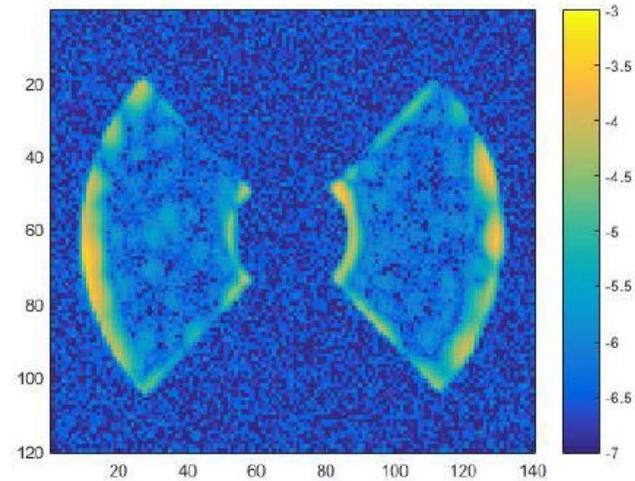


# Recent Lab Results

- Batch process estimator with two pairs of probes
- Stroke minimization controller
- Two BMC DMs with 952 actuators on each
- Achieved  $2 \times 10^{-7}$  contrast within  $6-11 \lambda/D$  and  $9 \times 10^{-7}$  contrast  $5-14 \lambda/D$



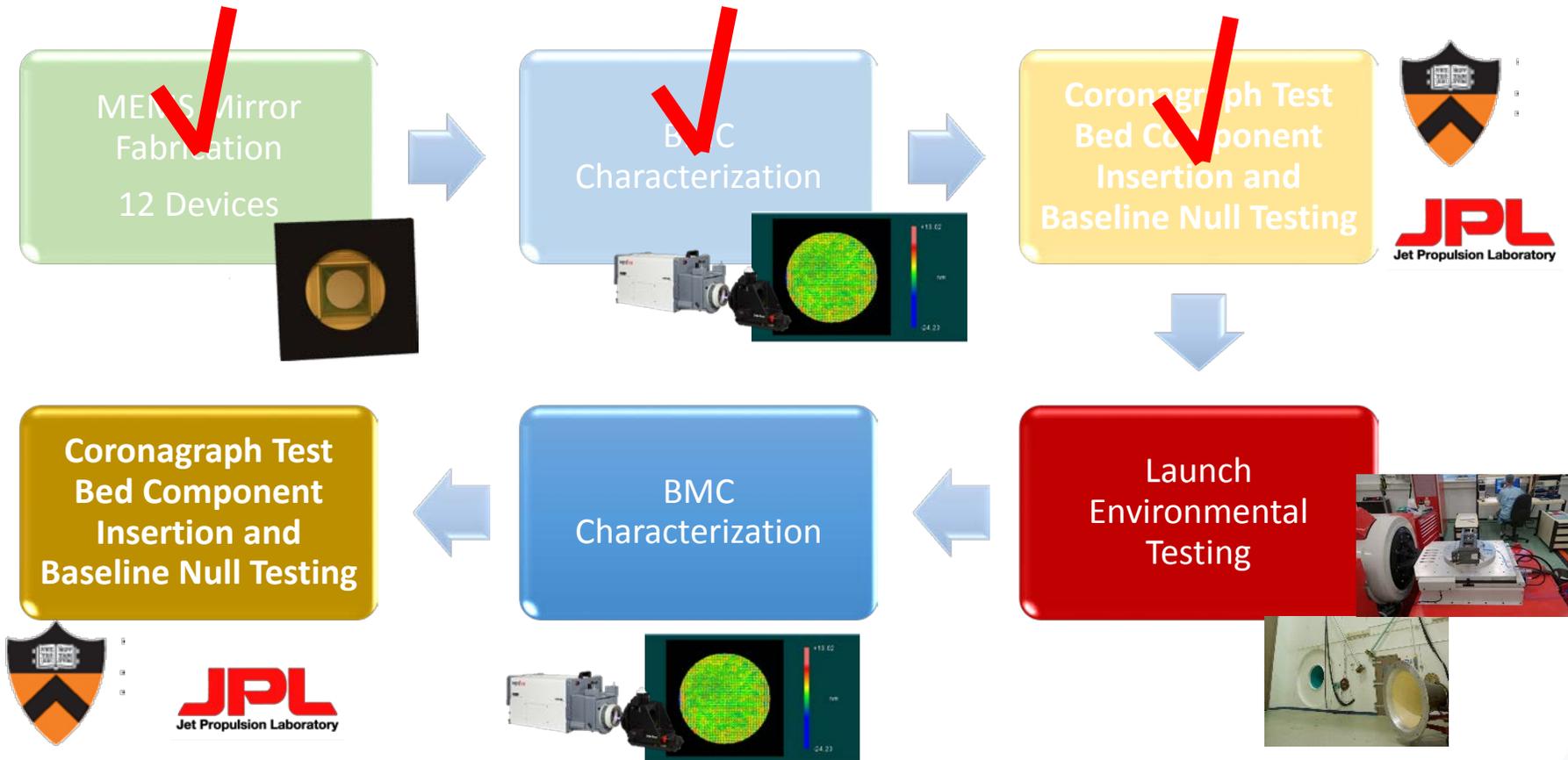
6-11  $\lambda/D$



5-14  $\lambda/D$

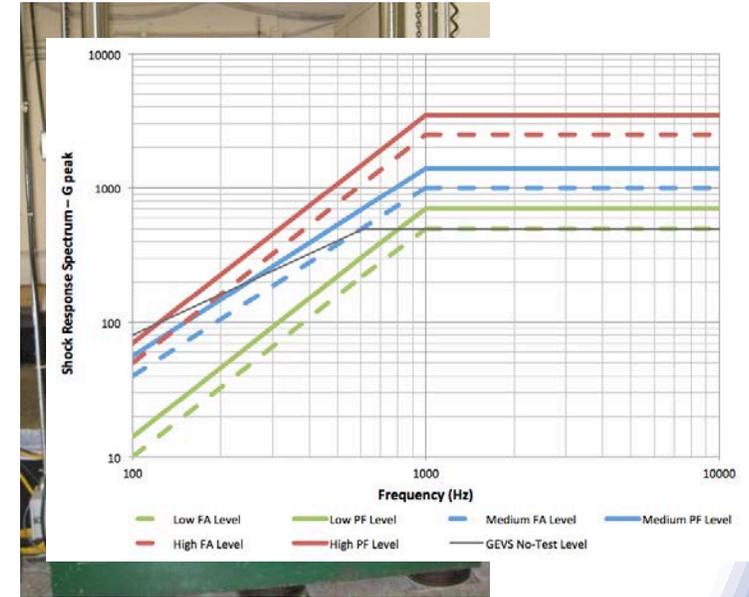
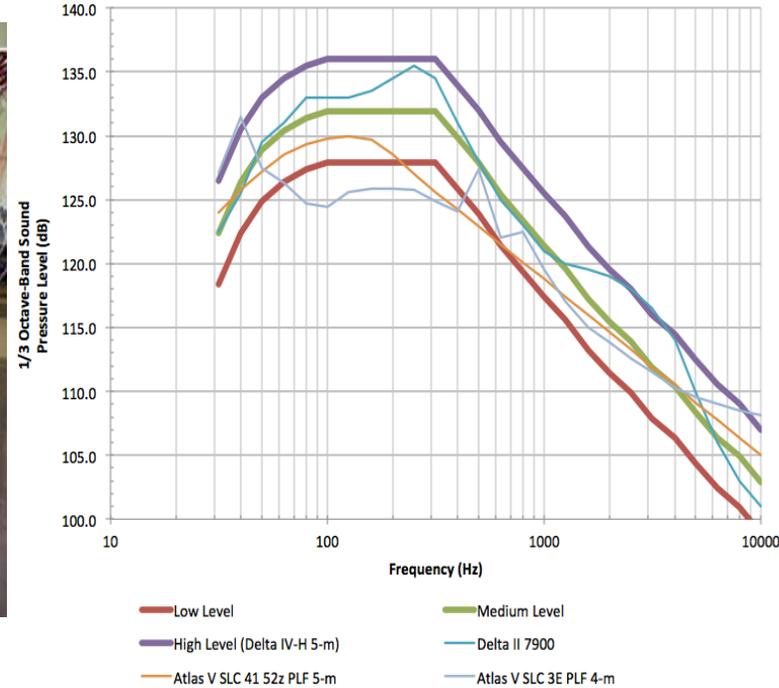
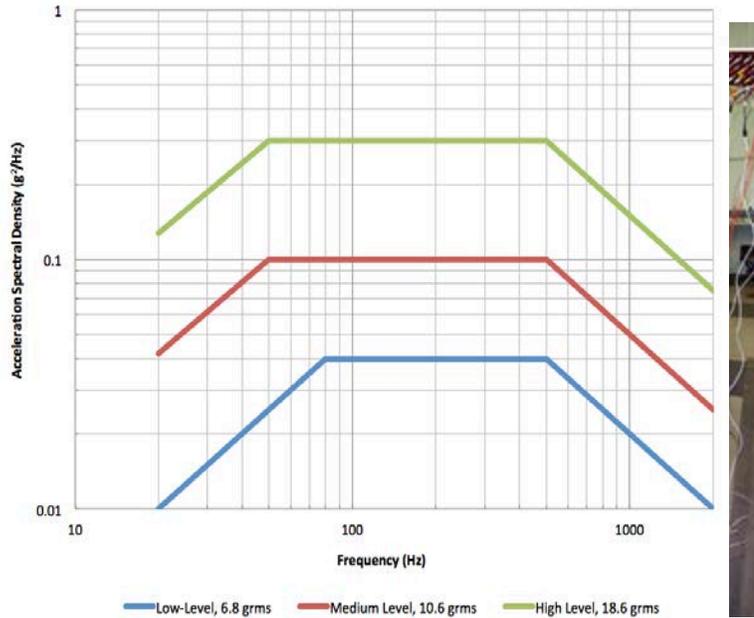


# Project Flow





# Environmental Testing



Vibration

Random and Sinusoidal

Acoustic

Shock



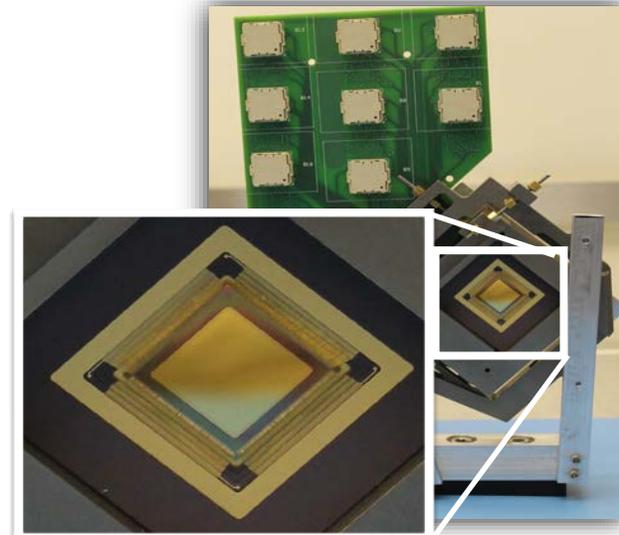
# Outline

- BMC DM Technology
- DM Technology  
Development and  
Advancement
- **Space astronomy operations**
- Ground astronomy  
operation
- Conclusion

# THE PICTURE(-B) SOUNDING ROCKET

PI: Supriya Chakrabarti, UMASS Lowell  
November 2015

- Reflected light from Exoplanets
- Scattered Light from Exozodi
- Visible Light Coronagraphy (in space)
- Active wavefront control

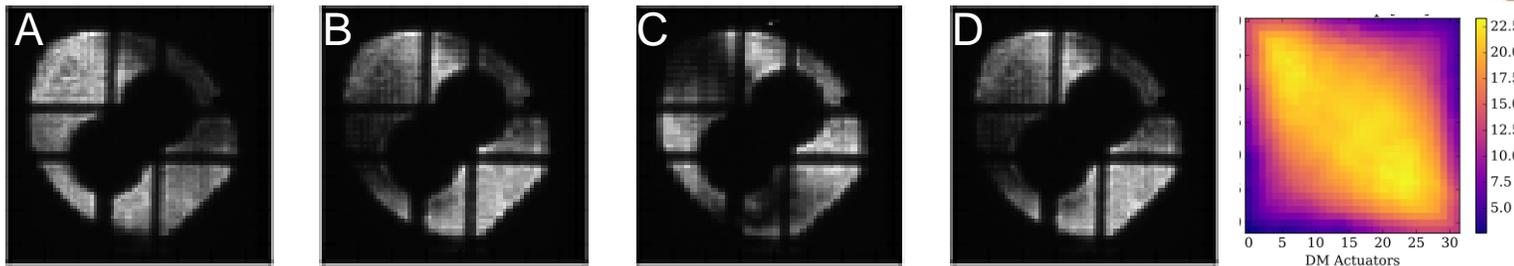


DOUGLAS 2016, COURTESY UML

The DM was powered in flight.

Deformable mirror “flat” map applied in flight to remove curvature:

Flat *Flight* Wavefront Sensor Measurements of Pupil Plane Fringes:



DOUGLAS 2016





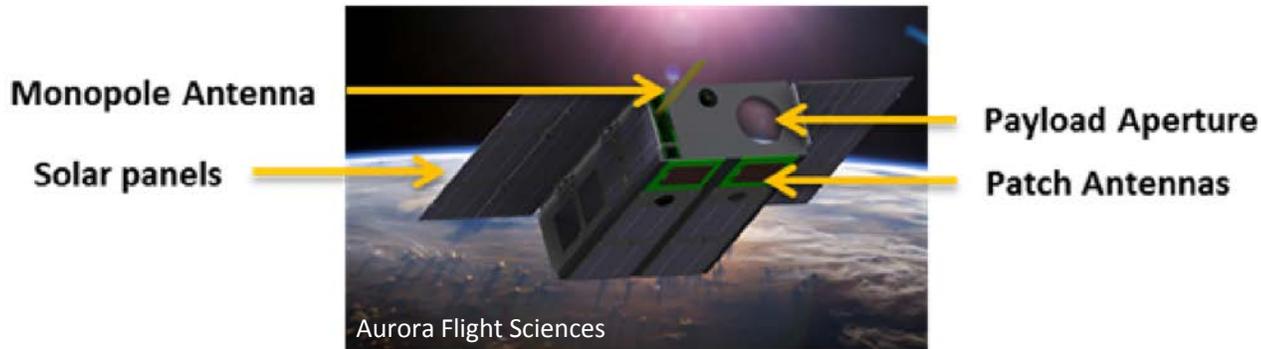
# Cubesat: Deformable Mirror Demonstration Mission (DeMi)

PI: Keri Cahoy, MIT ,John Merk, Aurora Flight Sciences

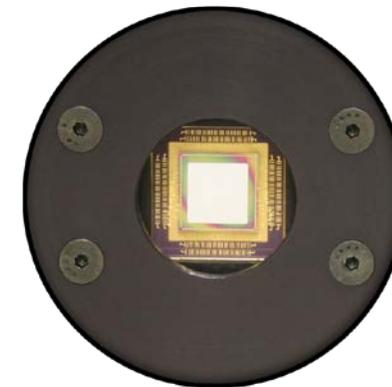
- DARPA Funded Cubesat program
- Validate and demonstrate the capabilities of high actuator count MEMS deformable mirrors for adaptive optics in space.
- Characterize MEMS deformable mirror operation using both a Shack Hartmann wavefront sensor as well as sensorless wavefront control.



Space Telecommunications,  
Astronomy, and Radiation Lab



Proposed mission configuration

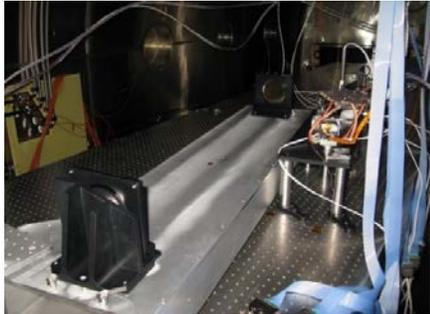


Planned use of Multi-DM

# EXoplanetary Circumstellar Environments and Disk Explorer (EXCEDE)



Final Broadband Milestone Results



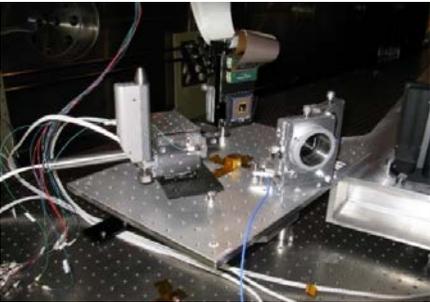
$\lambda_0 = 650\text{nm}$ , Bandwidth = 10%

- Test A

Time interval: 67 min

1.2– 2.0  $\lambda_0/D$ :  $1.35 \times 10^{-5}$

2.0–11.0  $\lambda_0/D$ :  $2.82 \times 10^{-7}$



- Test B

Time interval: 816 mins

1.2– 2.0  $\lambda_0/D$ :  $1.29 \times 10^{-5}$

2.0–11.0  $\lambda_0/D$ :  $3.14 \times 10^{-7}$

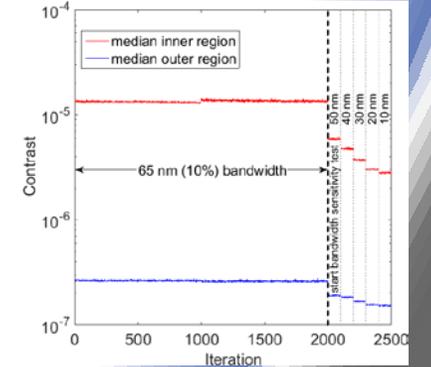
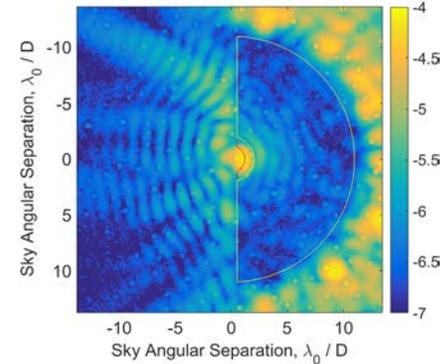
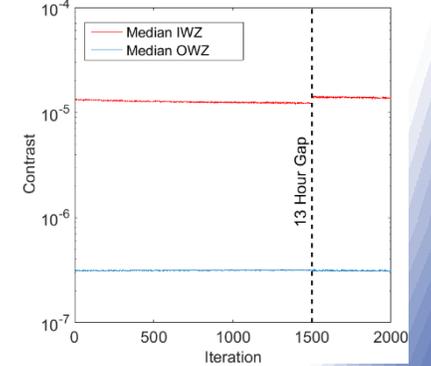
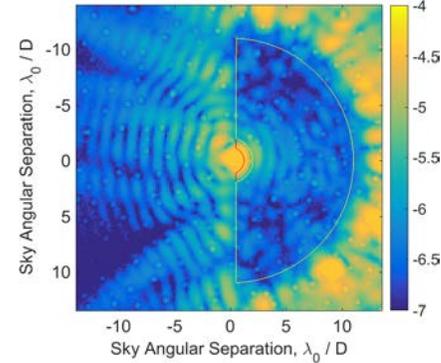
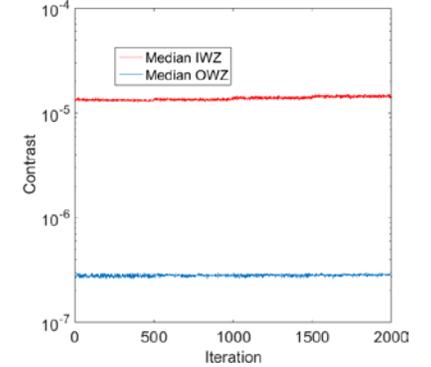
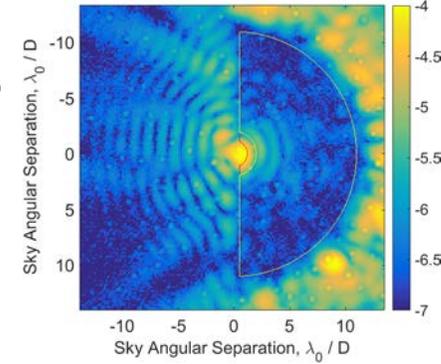


- Test C

Time interval: 61 mins

1.2– 2.0  $\lambda_0/D$ :  $1.33 \times 10^{-5}$

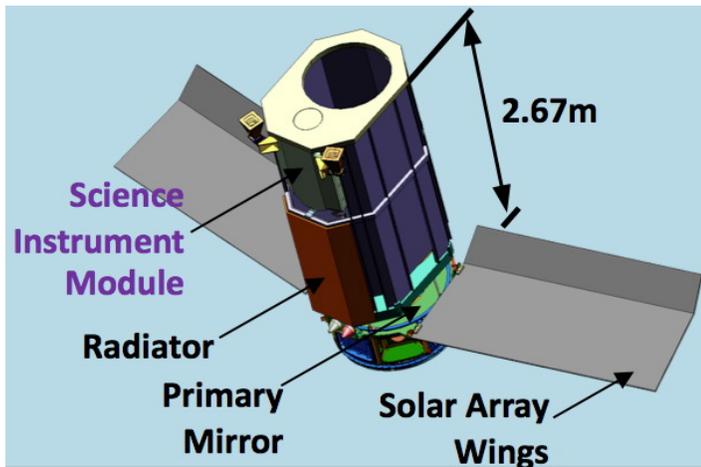
2.0–11.0  $\lambda_0/D$ :  $2.63 \times 10^{-7}$



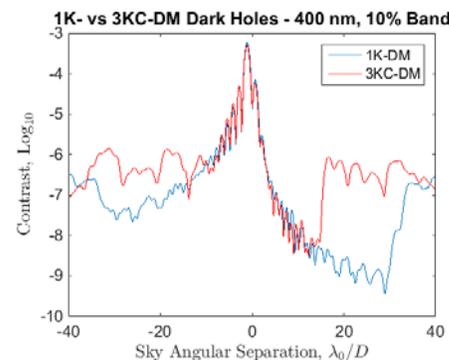
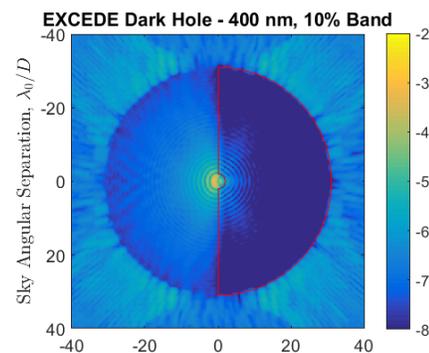
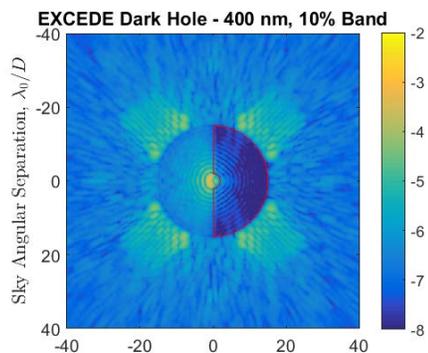
Lockheed Martin Vacuum Chamber



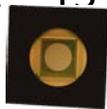
# EXCEDE Proposing for the 2016 MidEX AO



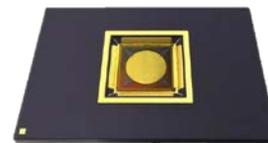
- Technical specs:
  - 0.7m primary, TMA unobstructed optical telescope
  - PIAA Coronagraph
- Mission overview
  - Survey of  $\sim 350$  nearby exoplanetary systems
- Science Capabilities
  - Circumstellar debris systems including the habitable zone
  - Gas giants (if sufficiently bright)



1K Boston MEMS DM  
Outer Working Angle – 15 L/D

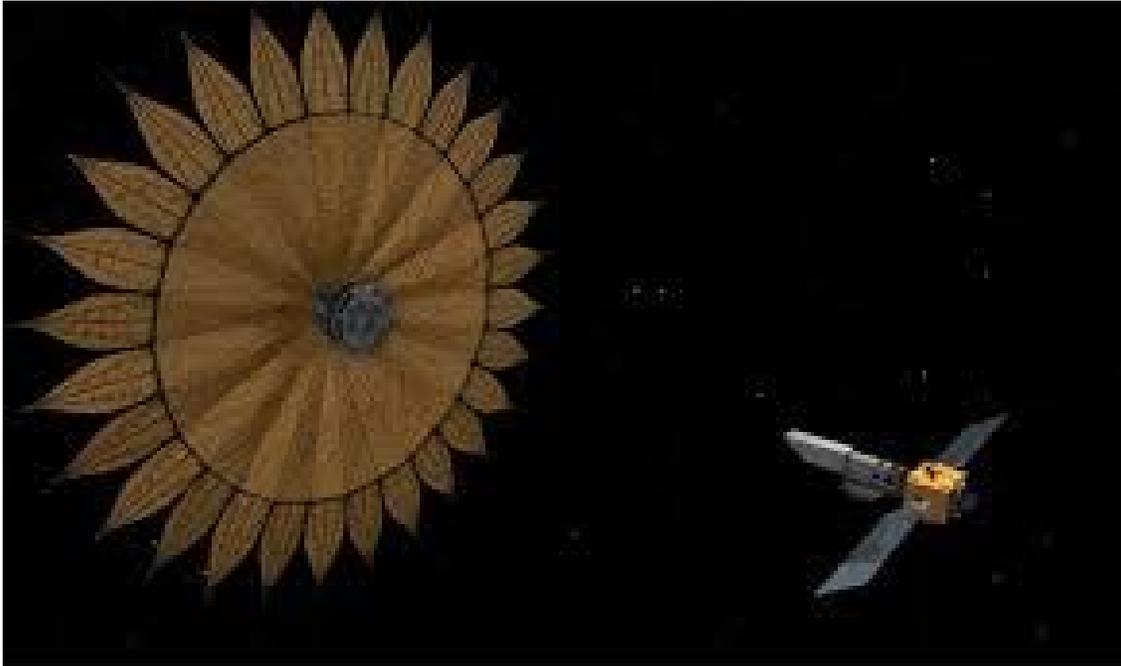


3K-C Boston MEMS DM  
Outer Working Angle – 31 L/D

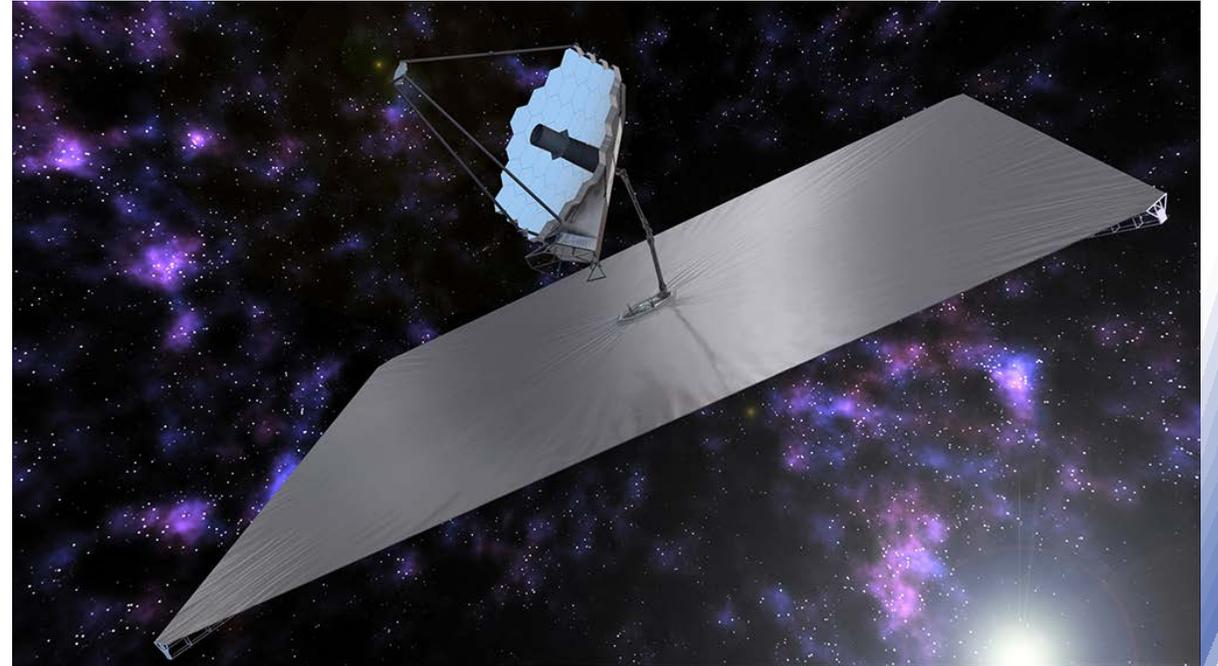




# Future Space Telescope Mission Concepts



Habitable Exoplanet Imaging Mission (HabEx)

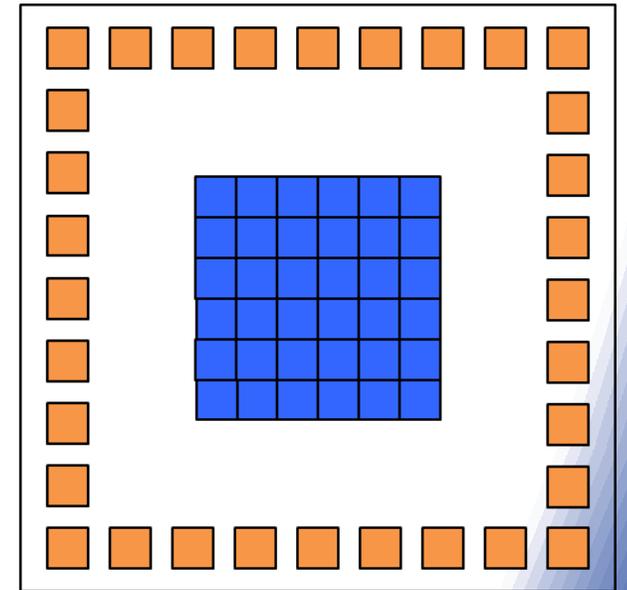
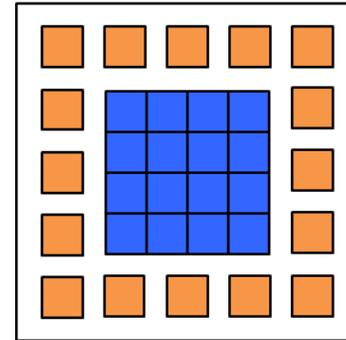


Large UV/Optical/IR Surveyor (LUVOIR)



# Need for Even Higher Actuator Count DM (10k +)

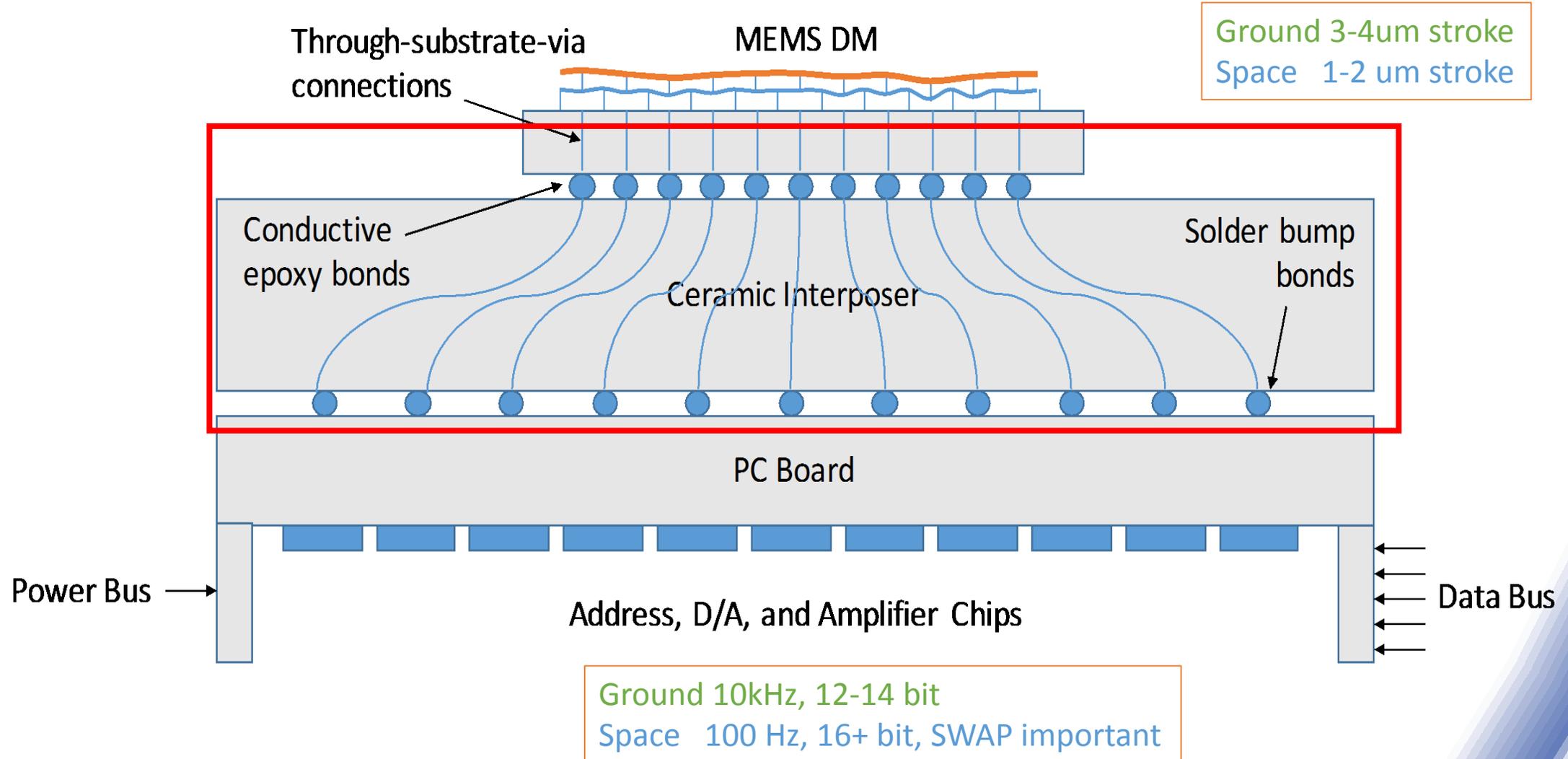
- For many next generation instruments, more actuators are needed
- Limited by electrical interconnects
  - Wirebond for each actuator
  - Span of active optical surface scales with  $N$
  - Span of the chip scales with  $N^2$
  - Limits number of die on a wafer
  - Increases the likely hood of a single point defect causing short/failure



By adding 2 more actuators across the aperture, the die size increased by  $\sim 3x$

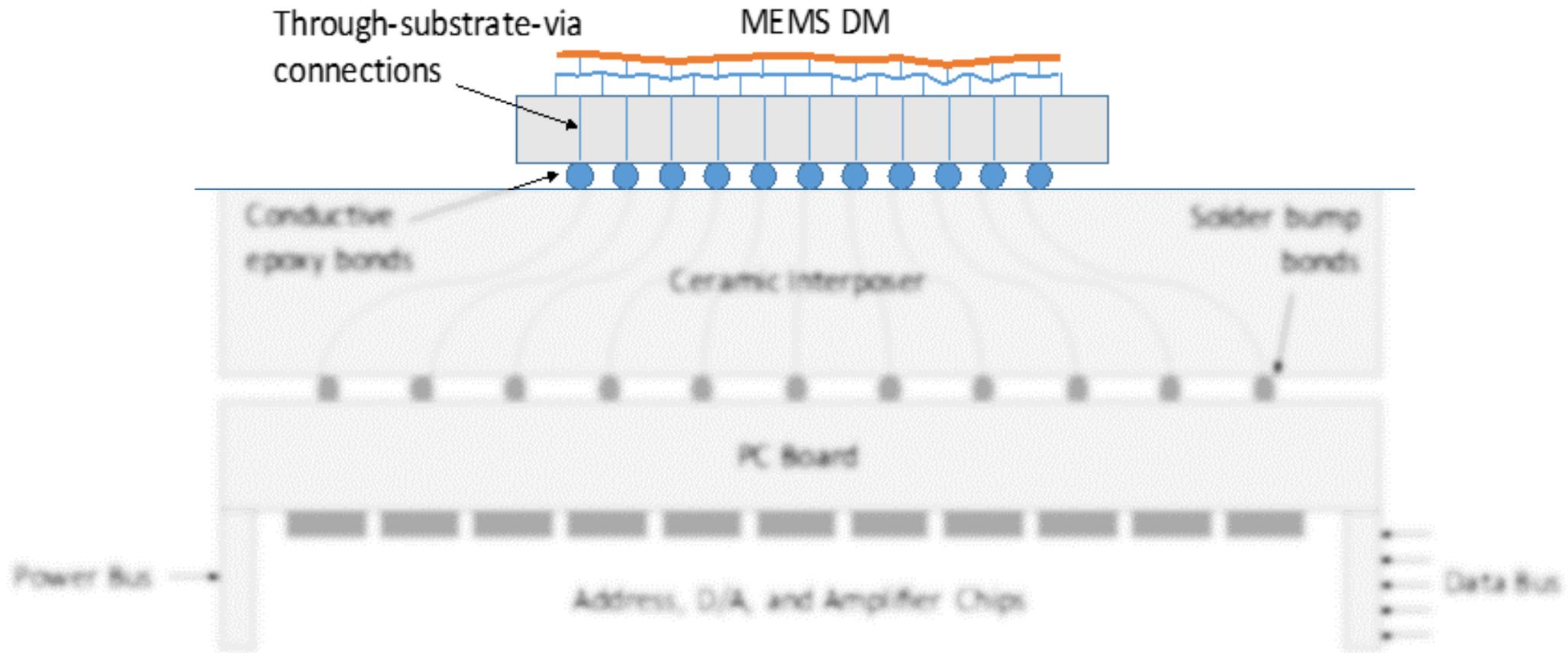


# Proposed Architecture (Concept 1)



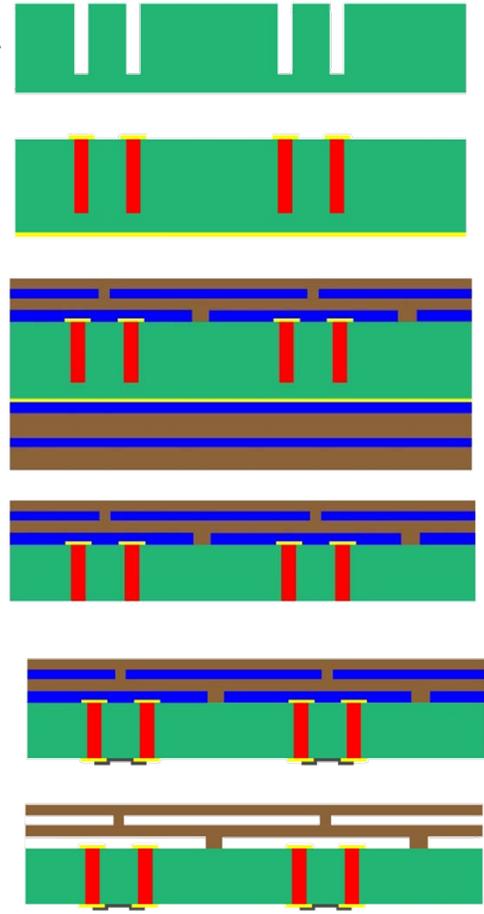


# Proposed Architecture (Concept)





# Through-Wafer-Via DM Fabrication Prototype



- |                       |                         |
|-----------------------|-------------------------|
| Highly Doped Wafer    | Sacrificial Oxide (PSG) |
| Via Isolation (oxide) | Poly Silicon            |
| Silicon Nitride       | Gold Pad                |

New process (and new foundry for manufacturing) relies on BMC heritage actuator and mirror design, but eliminates wire bonds and instead uses through-wafer-via (TWV) technology

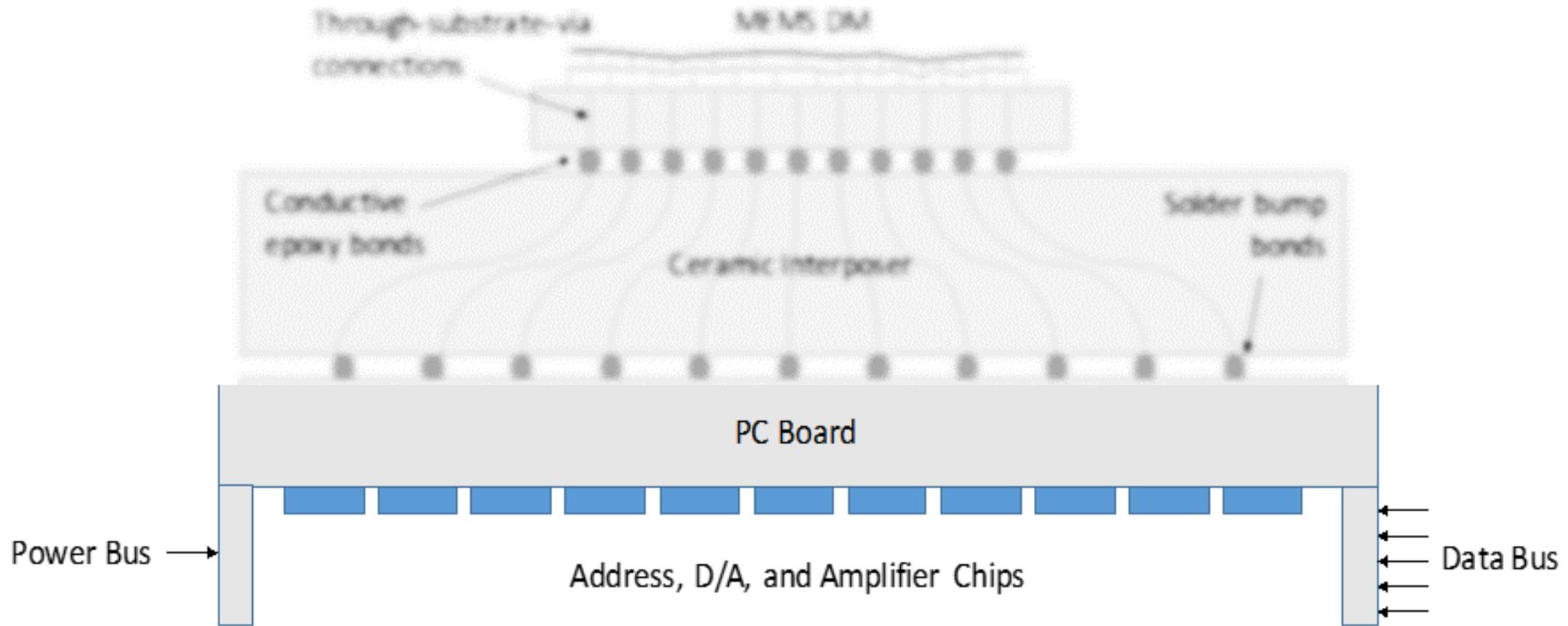
TWV is single crystal silicon: exceptionally low defect level allows major increase in device yield and reliability

Manufacturing challenge is shifted to packaging of TWV devices

In prototype project, 140 actuator, 500 actuator, and 2000 actuator devices were fabricated and tested

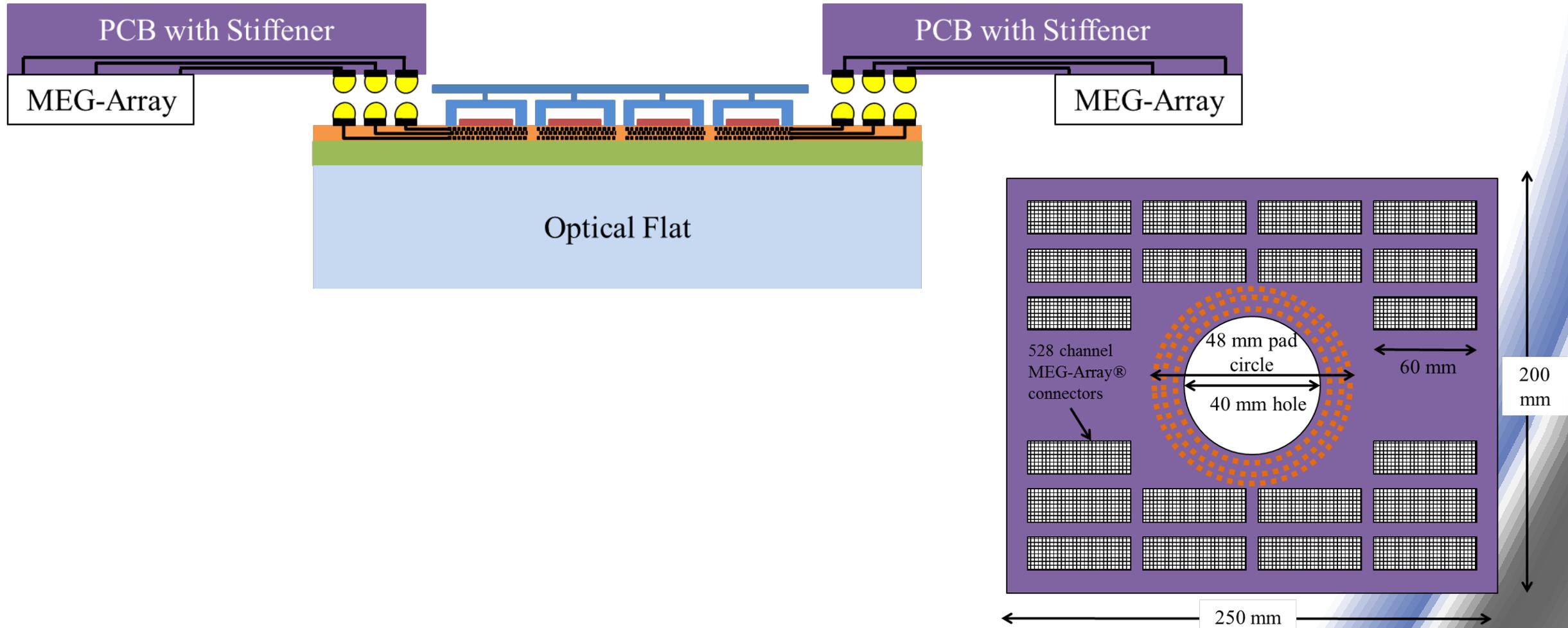


# Proposed Architecture (Concept)



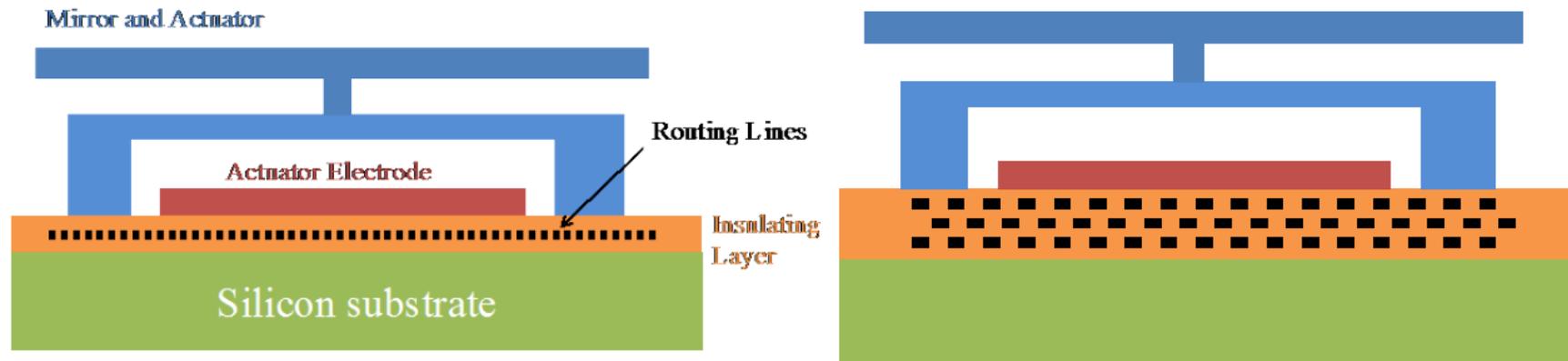


# Proposed Architecture (Concept 2)





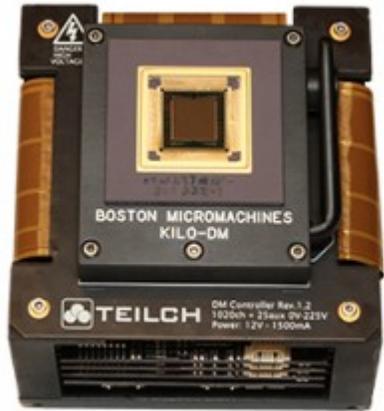
# Proposed Architecture (Concept 2)



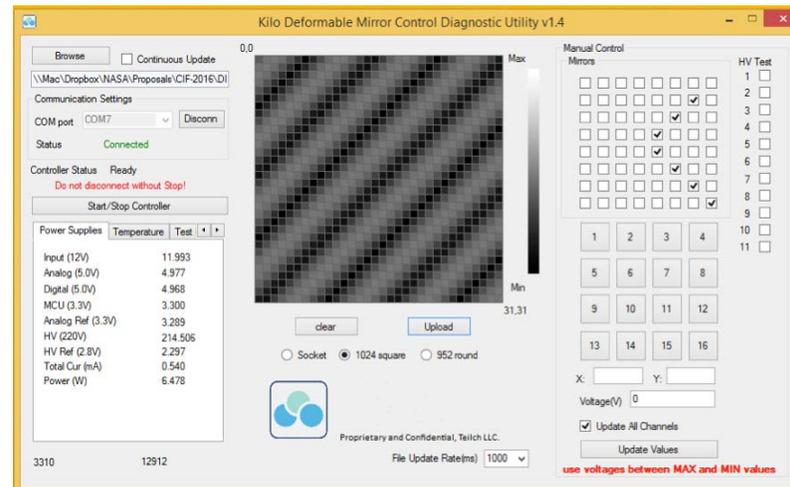
Multiple routing layers leading to high-density flip chip bond pads



# Electronics Design



- The controller has a volume of 90mm (w) x 90mm (l) x 54.6mm (h), w/o mirror and socket.
- It only requires a 12V power supply and consumes 6W.
- USB interface for data
- 0-215V, 16 bits
- Scalable technology for greater channel count





# Outline

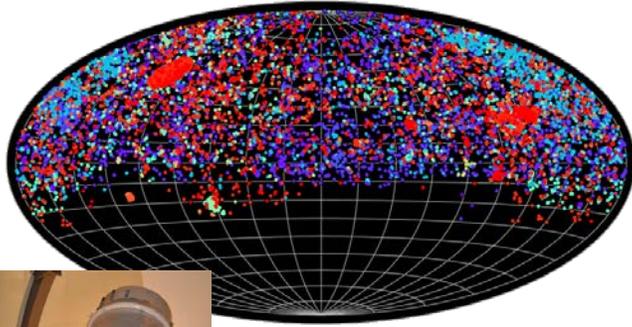
- BMC DM Technology
- DM Technology  
Development and  
Advancement
- Space astronomy operations
- **Ground astronomy  
operation**
- Conclusion



# On-Sky Instruments using BMC Mirrors

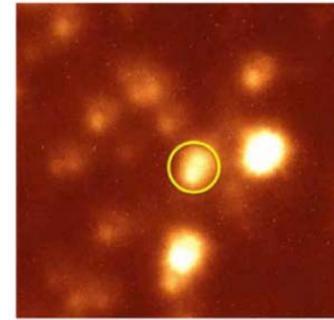
## ROBO-AO

- Multi-DM Installed Palomar 2011/ Moved to Kitt Peak 2015

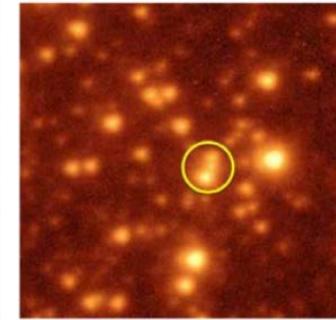


## Shane-AO, Lick Observatory

- Kilo-DM installed 2013
- Visible Light Laser Guidestar Experiments

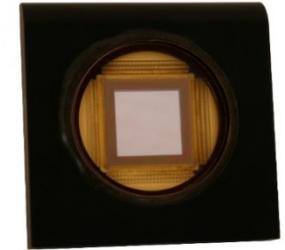


Shane AO off



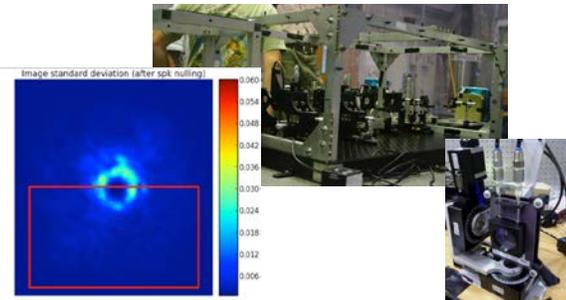
Shane AO on

Portion of the M92 globular cluster taken in H band.



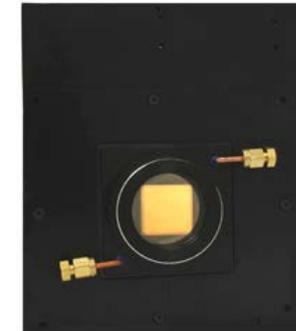
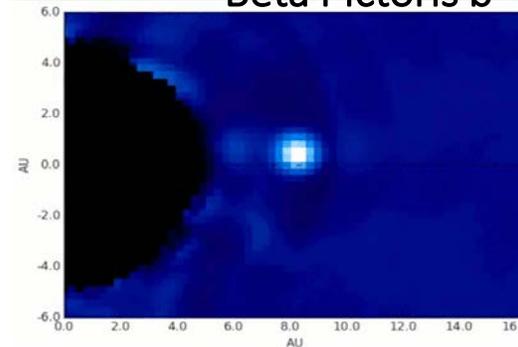
## SCEXAO, Subaru telescope

- 2040 installed 2013



## Gemini Planet Imager, Gemini South

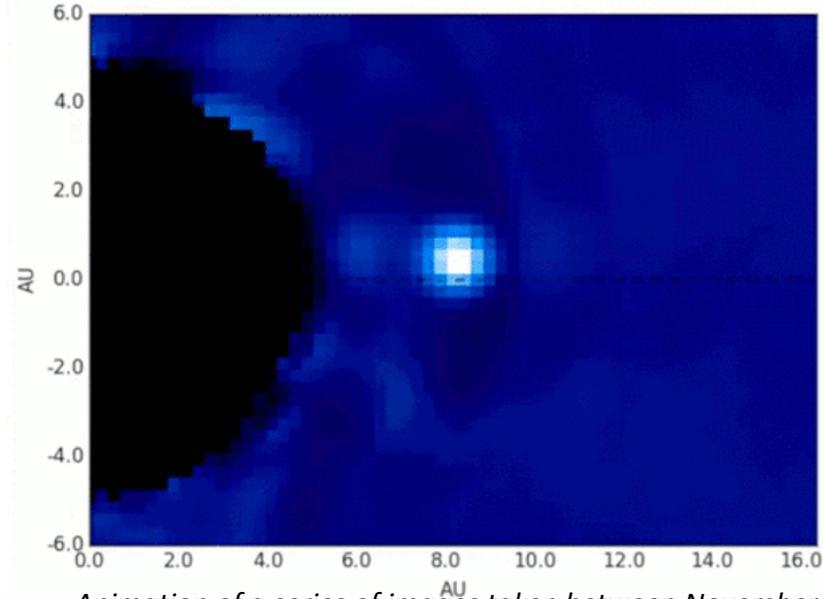
- 4092 installed 2013
- Beta Pictoris b**



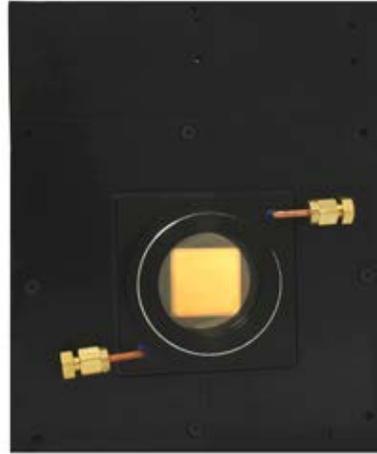


# Gemini Planet Imager: 4K DM

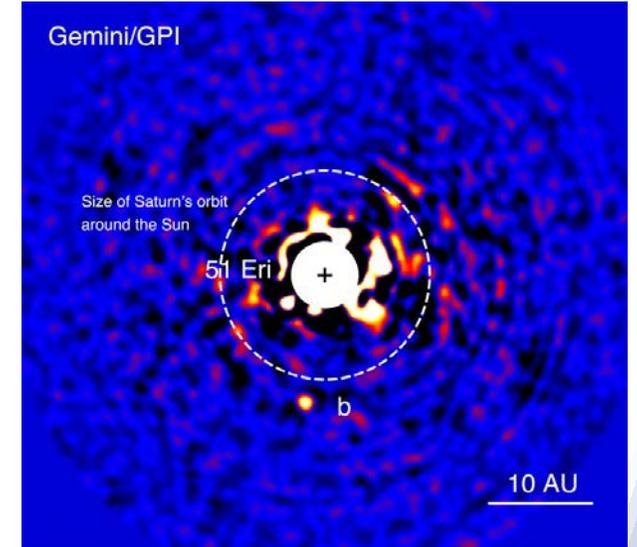
Beta Pictoris b



Animation of a series of images taken between November 2013 and April 2015 with the Gemini Planet Imager (GPI)  
Image credit: M. Millar-Blanchaer, University of Toronto; F. Marchis, SETI Institute

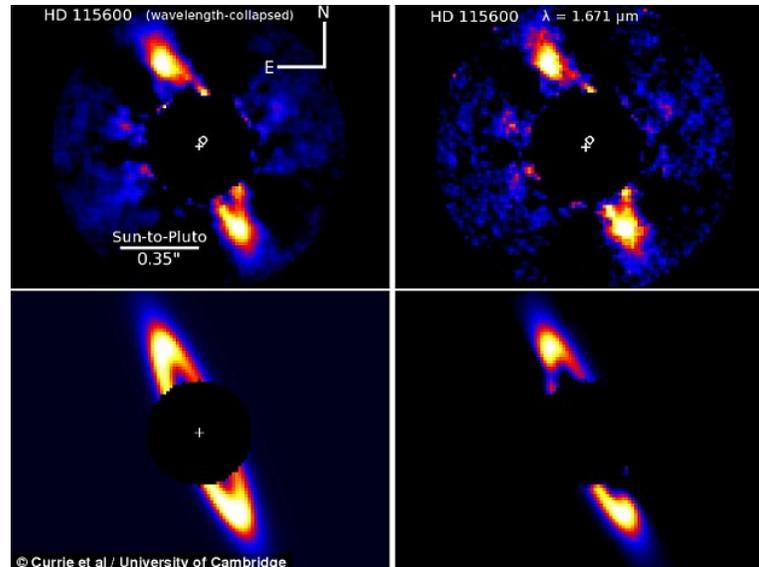


Young Jupiter 51 Eridani b



Discovery image of the exoplanet 51 Eridani b taken in the near-infrared light with the Gemini Planet Imager on Dec. 21, 2014. Image credit: Gemini Observatory and J. Rameau (UdeM) and C. Marois NRC Herzberg

HD 115600 ring of dust and gas



The bright disc is located at a distance similar to Pluto from the sun in our own solar system, which is in the Kuiper Belt.

Young star HR4796A

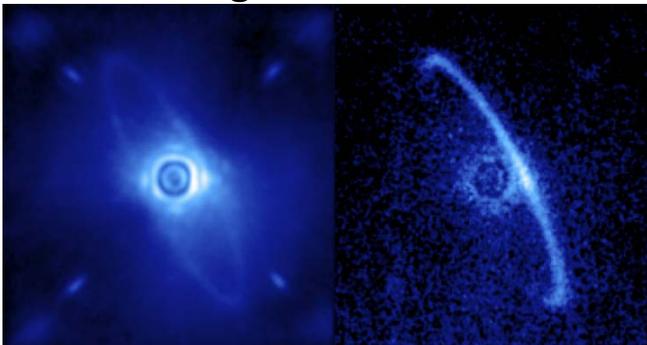
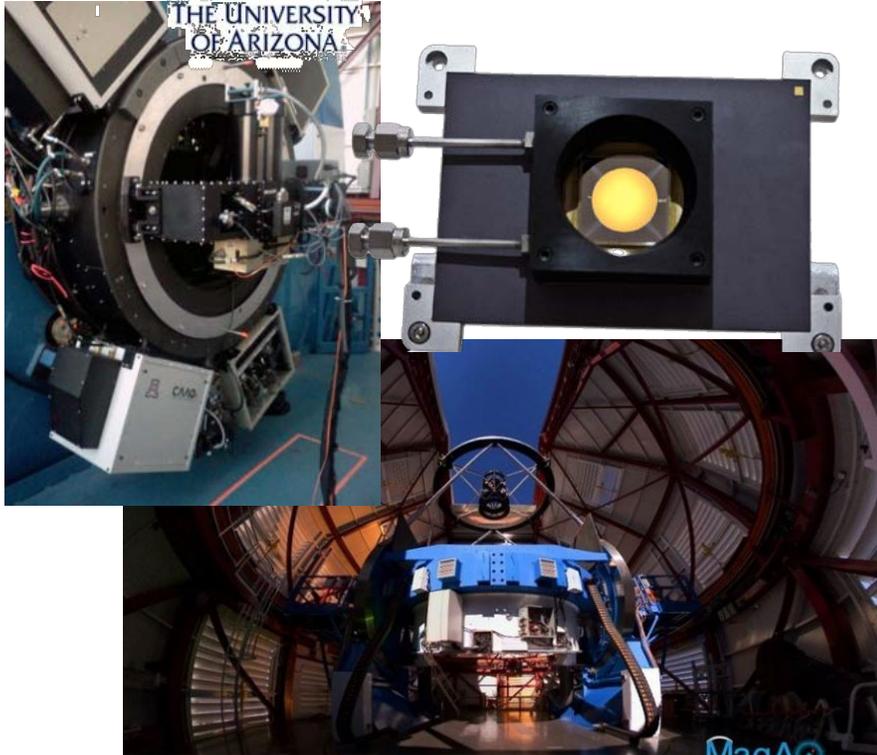


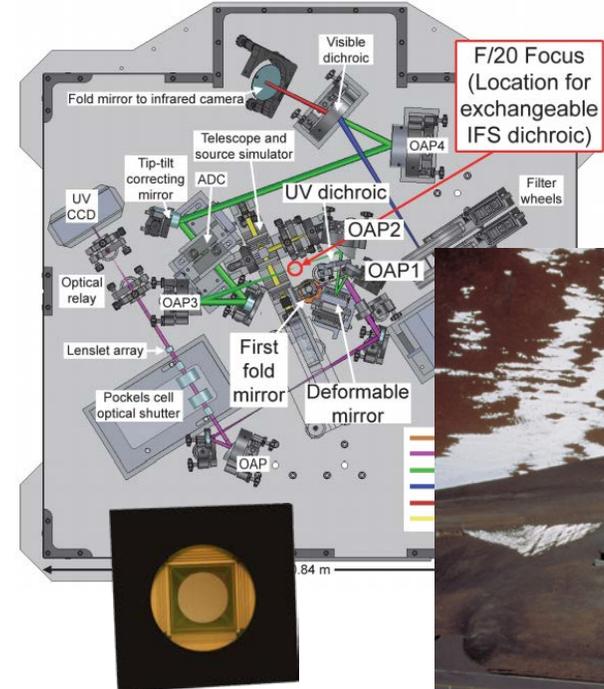
Image credit: Processing by Marshall Perrin, Space Telescope Science Institute



# Next Instruments



MagAO-X



Rapid Transit Surveyor

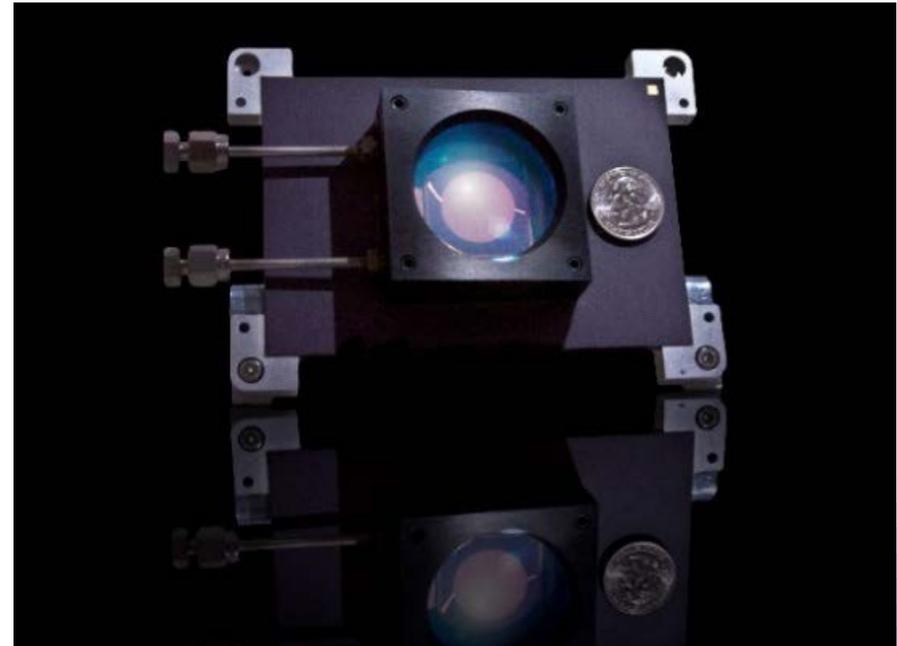


# Conclusion

- MEMS DM have been proven in astronomical instrumentation
- Continued technology development is ongoing
- Poised for next generation instruments, but development needs to occur.

## Acknowledgements

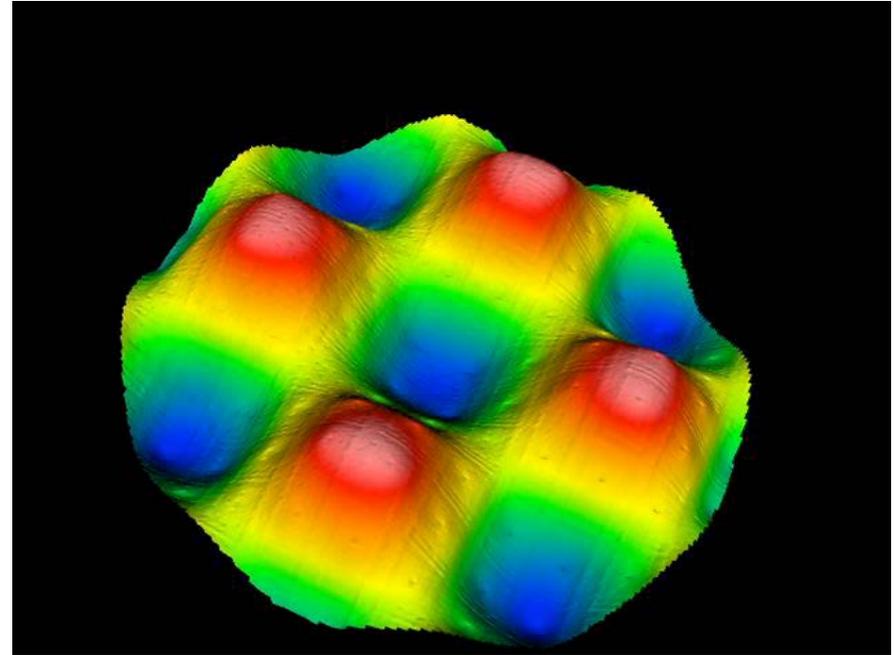
- Funding from NASA
  - Contract#: NNH12CQ27C TDEM/ROSES
  - Contract #: NNX16CP14C NASA Phase II SBIR
  - Contract#: NNX15CP39P NASA Phase I SBIR





# Thank You

Questions?



Paul Bierden, [pab@bostonmicromachines.com](mailto:pab@bostonmicromachines.com)